

## Inertial Measurement Units – *IMU*

**Ayman El-Fataty**

BAE SYSTEMS – Advanced Technology Centre  
West Hanningfield Road  
Great Baddow, Chelmsford  
Essex CM2 8HN  
UNITED KINGDOM

### **ABSTRACT**

*It is recognised that Micro-Electro-Mechanical-Systems / MEMS will enable the development of new military capabilities. Such capabilities will allow the introduction of low-cost, “high-end” functionality, to military systems, thereby, extending their performance and lifetimes. Examples of such novel capabilities include the development of complete inertial and navigation units on a single chip.*

*These capabilities will be realised through developments in civil applications which will be advanced to satisfy the military requirements.*

*The development of inertial systems is a common goal of the military and commercial MEMS communities alike, and have been universally recognised as offering major advantages in terms of size, weight and cost over conventional systems. Early predictions of both cost and performance have not, as yet, been fulfilled and current state-of-art characteristics falls somewhat short of the required inertial performance. To date, the MEMS accelerometer performance is close to that demanded by most military systems, but the rate sensor remains the weak link in the chain.*

*Inertial systems, can be classified into two main subsystems:*

- **IRS** (Inertial Reference Systems) based on either optical RLGs (Ring Laser Gyros) and accelerometers or electromechanical systems.
- **AHRS** (Attitude & Heading Reference Systems), aided by GPS/GNSS (through hybridisation), to enable the use of less accurate accelerometers and gyros and, thereby, the incorporation of MST/MEMS for each sensor or a combination of accelerometer/gyro multi-sensor systems.

*This lecture will introduce the basics of microsystems design techniques, the advantages of such novel devices and the evolution of the designs towards the realisation of microsystem-based IMUs.*

### **AIMS OF THE LECTURE SERIES**

- Introduce MEMS to the Defence community / NATO
- Familiarise the audience with MEMS technology its potential and capabilities
- Acquaint the audience with specific MEMS components (e.g. Inertial and Opto-electronic devices)
- Introduce a few typical examples of commercial products
- Discuss (propose) technology roadmaps and insertion plans

*Paper presented at the RTO AVT Lecture Series on “MEMS Aerospace Applications”, held in Montreal, Canada, 3-4 October 2002; Ankara, Turkey, 24-25 February 2003; Brussels, Belgium, 27-28 February 2003; Monterey, CA, USA, 3-4 March 2003, and published in RTO-EN-AVT-105.*

# Report Documentation Page

*Form Approved  
OMB No. 0704-0188*

Public reporting burden for the collection of information is estimated to average 1 hour per response, including the time for reviewing instructions, searching existing data sources, gathering and maintaining the data needed, and completing and reviewing the collection of information. Send comments regarding this burden estimate or any other aspect of this collection of information, including suggestions for reducing this burden, to Washington Headquarters Services, Directorate for Information Operations and Reports, 1215 Jefferson Davis Highway, Suite 1204, Arlington VA 22202-4302. Respondents should be aware that notwithstanding any other provision of law, no person shall be subject to a penalty for failing to comply with a collection of information if it does not display a currently valid OMB control number.

1. REPORT DATE <b>00 FEB 2004</b>	2. REPORT TYPE <b>N/A</b>	3. DATES COVERED <b>-</b>	
4. TITLE AND SUBTITLE <b>Inertial Measurement Units IMU</b>		5a. CONTRACT NUMBER	
		5b. GRANT NUMBER	
		5c. PROGRAM ELEMENT NUMBER	
6. AUTHOR(S)		5d. PROJECT NUMBER	
		5e. TASK NUMBER	
		5f. WORK UNIT NUMBER	
7. PERFORMING ORGANIZATION NAME(S) AND ADDRESS(ES) <b>BAE SYSTEMS Advanced Technology Centre West Hanningfield Road Great Baddow, Chelmsford Essex CM2 8HN UNITED KINGDOM</b>		8. PERFORMING ORGANIZATION REPORT NUMBER	
9. SPONSORING/MONITORING AGENCY NAME(S) AND ADDRESS(ES)		10. SPONSOR/MONITOR'S ACRONYM(S)	
		11. SPONSOR/MONITOR'S REPORT NUMBER(S)	
12. DISTRIBUTION/AVAILABILITY STATEMENT <b>Approved for public release, distribution unlimited</b>			
13. SUPPLEMENTARY NOTES <b>See also ADM001658., The original document contains color images.</b>			
14. ABSTRACT			
15. SUBJECT TERMS			
16. SECURITY CLASSIFICATION OF:			17. LIMITATION OF ABSTRACT
a. REPORT <b>unclassified</b>	b. ABSTRACT <b>unclassified</b>	c. THIS PAGE <b>unclassified</b>	
			<b>SAR</b>
			<b>108</b>
			19a. NAME OF RESPONSIBLE PERSON

- Introduce related study groups, networks, associations and national/international programmes involved in MEMS
- Invite responses / comments and interest
- Solicit support for developments and research

### LECTURE OUTLINE

- Microsystems (MEMS / MST and Micromachines): an Introduction
  - Definitions
  - Fabrication techniques
- Military applications of microsystems
- Commercial applications of microsystems and markets
- Microsystems-based components for IMUs
  - Gyros
  - Accelerometers
- Inertial measurement units
- State of the art: Developments and commercialisation
- Future outlook and general trends

### LECTURE NOTES

#### Background

The AVT Panel and RTB have approved the formation of a MEMS Task Group (AVT 078 / TG 019) to define specific MEMS requirements for military applications, to assess MEMS status and COTS availability, to develop roadmaps for component and system insertion, and to suggest potential joint technology demonstrators. As part of this activity, the MEMS Task Group proposed holding a series of lectures covering some of the main developments in MEMS. More specifically, these lectures will address:

- An Introduction into MEMS Technology
- An Overview of Micro Power MEMS
- Applications of MEMS to Gas Turbines & Health Monitoring
- MEMS for Health Monitoring of Munitions
- MEMS for Fusing, Safing & Arming
- MEMS and Inertial Measurement Units – IMU
- Micro-Opto-Electro-Mechanical Systems – MOEMS
- Micro-Flow Control

The following notes have been, specifically, prepared for this series of lectures<sup>1</sup>. The notes are aimed to assist the audience through the lecture presentations which will include sufficiently more details and explanations.

---

<sup>1</sup> The contents and the information has been, primarily, derived from two sources: (1) BRAMMS; a CEPA 2.30 contract no. 98/RFP 02.30/014 on the Broad Requirements for Advanced Military Micro-Systems and (2) NEXUS; the European Network of Excellence in Microsystems.

## MEMS: Definitions

There are different definitions for Microsystems used in Europe, the USA and Japan:

In Europe:

**“A microsystem (*MST*) is defined as an intelligent miniaturised system comprising sensing, processing and/or actuating functions. These would normally combine two or more of the following: electrical, mechanical, optical, chemical, biological, magnetic or other properties, integrated onto a single or multichip hybrid”.** (Microsystems in the 4th Framework IT, Sept. 1996)

In the USA:

**“Microelectromechanical systems, or *MEMS*, are integrated micro devices or systems combining electrical and mechanical components, fabricated using integrated circuit (IC) compatible batch-processing techniques and varied in size from micrometers to millimetres. These systems merge computation with sensing and actuation to change the way we perceive and control the physical world”.** (MCNC, 1996)

In Japan:

**“*Micromachines* are composed of functional elements only a few millimetres in size which are capable of performing complex microscopic tasks”.** (Micromachine Centre 1996)

A drawback of these definitions lies in their, rather, narrow scope of interpretation. For example a micronozzle fabricated out of Nickel for fuel injection, produced by lithography and electroplating, or a microfilter produced in silicon would not belong to the aforementioned definitions, although they belong to this collective field of microstructures.

In essence, the definition of a microsystem is a fairly nebulous one; Basically, a microsystem is an “intelligent” device that may comprise any combination of actuators, controllers and sensors. These functional sub-systems could be electronic, optical, mechanical, thermal or fluidic. What sets microsystems apart from conventional devices is their close relationship to IC components both in terms of manufacturing techniques and their potential for integration with electronics. To date, microsystems are developed using a variety of micromachining and/or IC processing techniques to produce devices with micron-size features, having applications as diverse as inertial guidance controllers and asthma medication vaporisers.

Further generalisations for microsystems will include:

- ASIMS (Application-specific-Integrated-Micro-instruments)
- MOEMS (Micro-opto-electro-mechanical systems)
- MEMtronics (Micromechanical structures)
- Nanoelectronics (atomic / molecular)
- MESO-technology (Modules /w many microstructures)
- $\mu$ Engineering
- Smart structures

MST/MEMS devices and components are, in general, fabricated on silicon using conventional silicon processing techniques. Although silicon may be the ideal material for many applications, other materials are gradually becoming more commonly used. Over the past few years, promising materials have been

investigated for the development of advanced MST/MEMS products, suited specifically, for defence applications. Examples include:

- SOI, SiC, Diamond microstructures & films
- « Smart cut type » substrates ( SiC, II-VI and III-V, Piezo & Pyro & Ferro )
- Shape memory alloys
- Magnetostrictive thin films
- Giant magneto-resistive thin film
- II-VI and III-V thin films
- Highly thermo-sensitive materials

Common processing techniques that are used to “sculpt” mechanical structures include:

- bulk micromachining
- surface micro-machining
- high-aspect ratio micromachining (LIGA – Lithographie/Lithography, Galvanoformung/ Electroplating und Abformung/Moulding)

### Advantages of MEMS

Micromachining techniques and microsystems offer a number of currently realisable advantages as well as potential promises which include:

- Small size (volume, mass and weight) through miniaturisation
- Low power consumption
- Increased functionality
- Modular design methodology
- Low fabrication costs via mass production processes

### MEMS for Defence Applications

To date, MEMS technologies have been demonstrated to provide elements of intelligent functional characteristics both as commercial and development devices/components. Indeed, a significant amount of scientific literature reports on MEMS components such as:

- Accelerometers
- Chemical Sensors
- Electronic nose
- Flow Sensors
- Fluidic valves
- Geo-phones
- Gyroscopes
- Inclinometers
- Infrared Imagers
- Injection Nozzles
- Lab-on-chip
- Micro-bolometers
- Micro-channels
- Micro-displays (DMD)
- Micro-mirrors
- Micro-motors
- Micro-optics
- Micro-positioners

- Micro-spectrometers
- Micro-tip AFM
- Micro-Thrusters
- Micro-tweezers
- Micro-relays
- Optical Filters
- Optical Switches
- Pressure Sensors
- RF components
- Temperature Senso

Over the past few years, the automotive industry has become a major user of MEMS devices for air-bag sensors. Printer manufacturers also continue to invest heavily in this technology for the development of, high resolution, micromachined ink-jet printheads. The pharmaceutical and medical businesses are also keen to apply this technology to their products as are the telecommunication industries. Indeed, it was confirmed that the, world-wide, MEMS market tripled by the year 2002 to approximately \$38bn and is estimated to increase to \$60bn by 2005.

Studies have established that most of the future military applications will have the following, generic, system requirements:

- Intelligent / unmanned operation
- Inter-linked communication channels
- Multi-sensing capabilities
- Inertial Navigation Systems
- Integrated Fluidic Systems
- Optical devices and systems
- Displays and adaptive optics
- Radiation hardness
- Ultra-Electronic Systems:
  - Massive computer operations (trillions of operations per sec.)
  - Massive storage (terabits / sq.cm)
  - Low power (nanowatts / gate)

These, generic, requirements, will form the basis of applications which are common across the various military platforms. More specifically, land, sea, air, space and missile applications will require one or more of the following functions:

- Nuclear & Bio/Chemical Sensors
- Micro Un-manned aerial / underwater vehicles
- Covert, autonomous, unmanned ground sensors, detection and treatment systems
- Optical systems and Imaging systems
- RF Components and Communication
- Distributed, agent-based, Evaluation & Sensor Array Systems
- Energy / Power generators
- Microthrusters
- Inertial Instruments

## Inertial Measurement Units – IMU

---

- Mass Data Storage units
- Fluid Sensing, control & Transport
- Fuel Storage systems
- Arming & disarming

It is recognised that MEMS will help enable the development of these new military capabilities. Such capabilities will allow the introduction of low-cost, “high-end” functionality to military systems, thereby, extending their performance and lifetimes. Examples of such novel capabilities include the development of:

- Complete inertial navigation units on a single chip.
- Distributed sensing systems for monitoring, surveillance and control.
- Miniature and integrated fluidic systems for instrumentation and bio-chemical sensors.
- Embedded sensors and actuators for maintenance and monitoring.
- Identification and tagging systems using integrated micro-opto-mechanical MEMS.
- Smart structures and components.
- Mass storage and novel display technologies.
- Systems-on-a-chip with increased packing density and robustness.

These capabilities will be realised through developments in civil applications which will be advanced, if necessary, to address the military requirements.

In the context of military systems, the performance of MEMS devices must, clearly, satisfy the stringent specifications and environmental conditions expected to be posed by such applications.

In general, such operational and environmental requirements will also include; resilience to radiation, high temperatures (including sharp cycles in excess of 150 °C), vibration & shock (up to 100,000g levels of force) and electromagnetic compatibility. In addition the technologies should take into account the non-accessibility after launch, in certain circumstance, which dictate the need for “first-time-right” qualification.

Packaging for military MST/MEMS is, therefore, more critical than that for commercial applications of the technology, and even there it is regarded as a prime discriminator between commercial success and commercial failure. For commercial microsystems, packaging is said to account for 80% of the cost and 80% of the failures. The proportions of both in a military environment is not likely to be lower, and will in all probability be even higher.

Packaging is inextricably linked to the environmental specifications, and is often all that stands between the delicate and complex microstructure and the hostile world around it. Properly designed and implemented, it can protect the microsystem from the worst excesses of a military application. It is significant that for existing MEMS products (e.g. those developed specifically for automotive use), the only feature that distinguishes the commercial product from variants marketed as say “aerospace quality” is the packaging and final testing.

## **MEMS ACCELEROMETERS AND GYROS**

### **Acceleration Sensors**

The primary market in terms of unit sales for accelerometers is that of the automotive business. In this context, such devices serve applications such as airbag deployment, vehicle dynamics control and active suspension. A fully equipped airbag system may contain up to seven accelerometers whilst an active suspension system typically uses between three to five of such devices. Other applications are in (Anti lock brake) ABS-Systems or as tilt-sensors for intruder alarm and detection.



**Side Airbag Acceleration Sensor.**  
Source: Bosch

### **Technology**

Silicon micromachining is by now the dominating technology for the accelerometer markets where small size, low cost and high volume are required. For the automotive market it is estimated that more than 90% of all accelerometers supplied in 2000 were silicon micromachined. The remaining few were mostly of the piezo-ceramic type.

Currently, the majority of the silicon accelerometers are of the surface micromached type. However for low-g, high-performance applications bulk-micromaching is still a widely used technology. Here functional advantages overcome the higher production cost.

Recently, alternative techniques such as thermal measurement principles, using on silicon membranes, have been proposed for low-frequency tilt measurements (Vogt, Memsic).

### **Major Manufacturers include:**

Europe: Bosch, VTI-Hamlin, Temic, Sensoror

USA: Analog Devices, Motorola

Japan: Denso

### **Gyroscopes**

Gyroscopes are inertial sensors used to measure the rate of rotation (measured in degree/s) of a body with respect to a reference system.

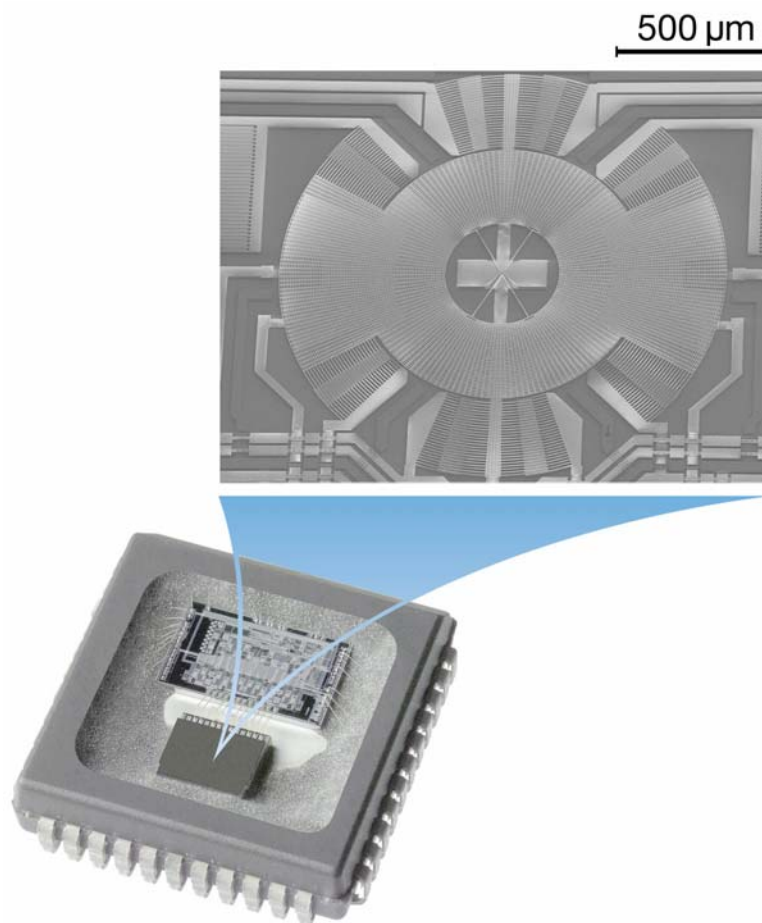


## Inertial Measurement Units – IMU

Gyroscopes are used in all kinds of applications where the rotational movement of a body or structure needs to be monitored. One of the main applications for such devices is in navigation. Most navigation systems currently available are GPS-based. However gyroscopes can improve the accuracy of the system and are essential as a backup when satellite signals are unavailable. In recent years several, new, automotive applications have been identified, including vehicle dynamics control and rollover-protection. These applications are expected to constitute a major part of the unit volume market over the coming years.

Other applications which will entail the development of improved gyros, include:

- Vehicle navigation
- Avionics navigation
- Navigation for space and weapons applications
- Vehicle dynamics control systems
- Rollover-protection
- Image stabilization for cameras
- Handheld navigation systems
- Medical applications



**Silicon Micromachined Gyro for Application in Navigation Systems.**  
Source: Bosch

## Technology

Gyros measure the rotation either by means of the Coriolis force or by the relative phase shift of coherent light circling in opposite directions in two glass fibres (FOG).

The FOG, which is not considered to be a microsystem, sells at prices of several thousand dollars for high end applications requiring resolutions of up to  $0.001^\circ/\text{s}$  (e.g. aerospace or weapons applications). These stringent requirements will probably not be satisfied by MST-based gyros in the near future.

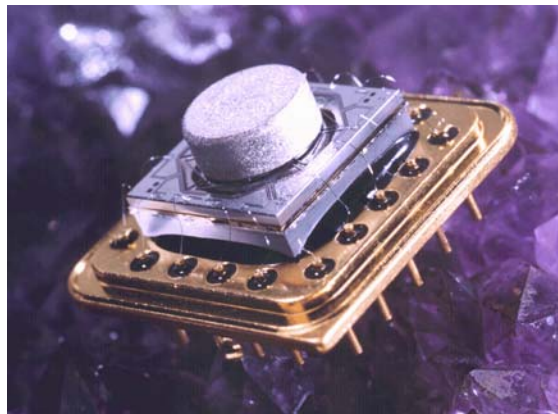
The strength of MST-base gyros lies in the low to medium performance applications where mass-production is required. Two main technologies are now established in this segment:

- Quartz tuning forks
- Silicon micromachining

Gyros manufactured by both technologies use the Coriolis effect. Drive and detection for quartz forks are usually piezoelectric, whilst silicon based gyros use piezo-, electrostatic or electromagnetic drives and piezoelectric or capacitive detection schemes.

Quartz technology has been successfully used for many years by companies such as Systron Donner, Panasonic and Murata, while the first silicon based sensors have been commercialized by Bosch in 1998. In the future a trend towards silicon is anticipated because it is amenable for mass production in batch processes and holds the potential for continued size reduction and integration with electronics. Many companies are currently involved in research, development and commercialisation of Si-based gyros such as Analog Devices, Delco, Sensoror, BAE SYSTEMS, Samsung, Murata and Sumitomo.

Resolution requirements for the low to medium performance applications are in the order of  $0.01^\circ/\text{s}$  to  $2^\circ/\text{s}$  range and can be achieved by either technology.



**BAE SYSTEMS' Si Gyro.**

### Major Manufacturers include:

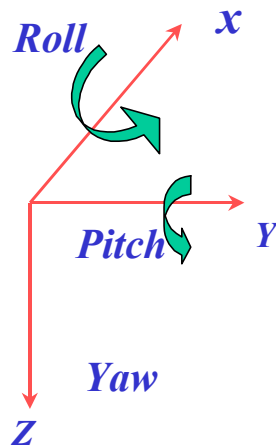
Europe: Bosch, BAE SYSTEMS

USA: Systron Donner

Japan: Denso, Sumitomo, Panasonic, Murata

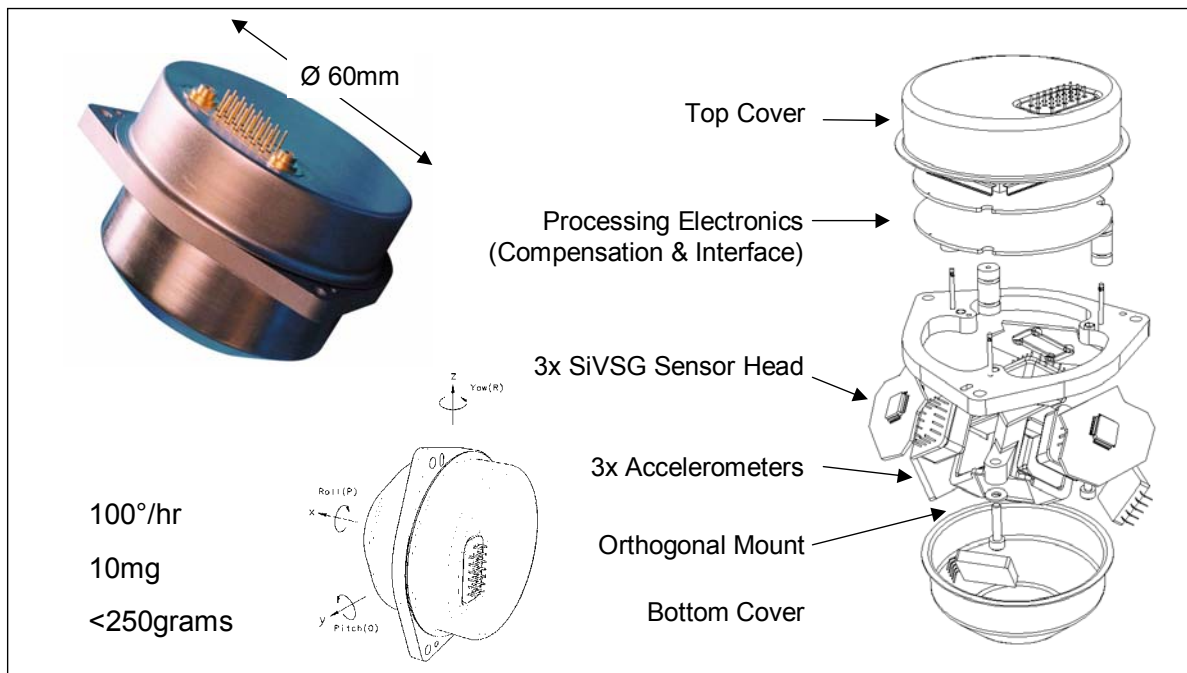
**INTERTIAL MEASUREMENT UNITS**

The measurement of Roll, Pitch and Yaw entails the use of 3 linear accelerometers and 3 rate gyros to measure rotational velocity. These components are geometrically positioned to provide X, Y and Z co-ordinate-based measurements, respectively:



IMU designs are, currently, being assessed by manufacturers including BAE SYSTEMS. Research is also underway at some organisations aimed at developing components capable of sensing inertia along orthogonal planes.

In summary, progress in the development of accelerometers, gyros and IMUs is likely to rely heavily on a market pull that is entirely driven by civil applications. Novel encapsulation, packaging and integration techniques will, however, be necessary to address the requirements of defence applications.



## THE CHALLENGES

Whilst the important role of MEMS is confirmed for future military platforms, further developments in the design and performance of these devices is, however, necessary in order to satisfy the stringent requirements set for military applications. More specifically (and typically):

- **Military specifications (including aircraft, missiles and munitions) are particularly demanding (for example):**

<b>Vibration:</b>	<b>20 to 3,000 Hz (for 5g to 20g)</b>
<b>Structural Resonance:</b>	<b>&gt; 3,000 Hz</b>
<b>Temperature:</b>	<b>-65°C to &gt; +125°C</b>
<b>Mechanical shock:</b>	<b>up to 100g for fighter aircraft up to 300g for missiles more than 15,000g for gun launched munitions</b>
<b>Angular Acceleration:</b>	<b>&gt;500,000 rad/S<sup>2</sup> (spinning gun launched munitions)</b>

Other, more generic, challenges will also need to be addressed, namely:

- **Military MEMS will depend, heavily, on the commercial / civil MEMS developments as low volumes, for the military markets, will attract high costs.**
- **Military product life-cycles exceed those for commercial / consumer products where, both process availability and product obsolescence become a major concern.**
- **Access to military-specific MEMS developments by the civil markets may have security implications.**
- **Repair of MEMS is not, normally, feasible and diagnostics is difficult.**

In spite of these hurdles, there is little doubt that microsystems will proliferate within military platforms providing intelligent functionality and enhanced performance.

Dr AYMAN EL FATATRY  
PhD BSc CEng  
Head  
Systems Department

BAE SYSTEMS  
Advanced Technology Centre  
West Hanningfield Road  
Great Baddow, Chelmsford, Essex CM2 8HN, Great Britain  
Tel: +44-1245 242101, Fax: +44-1245 242124

e-mail: [ayman.elfatetry@baesystems.com](mailto:ayman.elfatetry@baesystems.com)

Web Site: <http://www.baesystems.com>

Ayman received his BSc from Loughborough University of Technology, UK in 1978 and his PhD from the University of Kent, Canterbury, UK in 1986. He joined the General Electric Company's Hirst Research Centre in 1978.

From 1984 to 1989, he worked in the Optical Fibres Division, where he contributed to the development of various novel optical fiber components and to photonics research. From 1990 to 1994 his responsibilities steadily increased including managing R&D in high temperature superconductivity, vacuum microelectronics, micromachining and biosensors, and later Fuzzy Logic Control, vision systems, high performance computing, advanced signal processing techniques and olfaction.

During May 1995, following Hirst's amalgamation within GEC Marconi Materials Technology (GMMT), Ayman was given charge of a newly formed Applied Technology Laboratory encompassing several additional technologies on Modelling and Simulation, Control and Decision Algorithms. In May 1996, he was appointed manager of the Signal Processing, Control and Communications Laboratory, amalgamating all the theoretical and signal processing activities within one laboratory.

Following the re-organisation of the research centres within Marconi, in 1998, Ayman was appointed Business Group Manager for the Data Analysis & Techniques Group as well as Deputy Manager for the Communications & Information Systems Division based at the Marconi Research Centre. The Group has 40 qualified staff whilst the Laboratory has 80 staff in total. This research establishment has recently become part of BAE SYSTEMS Advanced Technology Centres.

Ayman is, currently, manager of the Systems Department of the Advanced Technology Centre. The Department has four main Groups of researchers: (1) Space Systems, dealing with SAR signal processing and algorithms, sensor data fusion and ground-station IFMS systems. (2) Intelligence Systems, encompassing work on mathematical techniques, control systems and data processing systems. (3) Communications Systems, directed towards defence applications and the battlespace. (4) Signal Processing Systems for rapid prototyping, noise and vibration control and high performance computing.

Finally, Ayman is also an active member of NEXUS, the European network of excellence in multi-functional microsystems, was prime co-ordinator of BRAMMS, a European collaborative project on Military MEMS/MST and is also involved in many other national and international initiatives in this field of technology.



**BAE SYSTEMS**

# **MEMS Aerospace Applications**

*Les Applications Aérospatiales des  
MEMS*

**An AVT-105 Lecture Series No. 235**

organised by the

**Applied Vehicle Technology Panel**

*Ayman El-Fatratry  
Head of Systems Department  
BAE SYSTEMS  
Advanced Technology Centre  
United Kingdom*







# **NATO RESEARCH AND TECHNOLOGY ORGANIZATION (RTO)**

## **APPLIED VEHICLE TECHNOLOGY (AVT) PANEL**

- **TASK GROUP “MEMS APPLICATIONS FOR LAND, SEA,  
AND AIR VEHICLES”**

**Task Group Chair: DR. KLAUS SCHADOW, STRATEGIC ANALYSIS, INC - US**

**Task Group Co-Chair: Dr. AYMAN EL-FATATRY, BAE SYSTEMS - UK**

### **Objectives (2000 - 2002):**

- (1) define military needs, status, and potential applications for MEMS components and systems,
- (2) select and prioritise applications,
- (3) explore potential collaborations,
- (4) develop roadmaps for potential R&D collaborations and joint technology insertions, and
- (5) write and submit final report.





# NATO RESEARCH AND TECHNOLOGY ORGANIZATION (**RTO**)

- **First Task Group Meeting:** was held October 10-12, 2000, Ankara, Turkey, in conjunction with the RTO Symposium “Unmanned Vehicles (UV) for Aerial, Ground, and Naval Military Operations”
- **The second meeting** was held May 7-9, 2001, in Loen, Norway, in conjunction with the RTO Symposium “Advanced Flow Management: Vortex Flows and High Angle of Attack – Military Vehicles”
- **The third meeting** of the Group will take place during AVT-099: Novel and Emerging Vehicle and Vehicle Technology Concepts, scheduled for April 22-26, Paris.
- PLUS **RTO Lecture Series “MEMS Aerospace Applications”**
  - Montreal, 3 and 4 October 2002**
  - Ankara: 24 and 25 February, 2003**
  - Brussels: 27 and 28, 2003**
  - Monterey: 3 and 4 March, 2003**



# Lecture Outline

- **Introduction to the Series**
  - **The Presenter**
- **Microsystems (Definitions)**
  - **Applications**
  - **The BRAMMS Report**
- **Principals & Configurations**
  - **COTS & Products**
  - **Accelerometers**
    - **Gyros**
    - **IMUs**
- **Markets and Opportunities**
  - **Trends and RoadMaps**



## **Aims of the Lecture Series**

- **Introduction to MST/MEMS**
- **Focus on specific applications & devices**
  - **COTS MEMS**
  - **Programmes and Initiatives**
    - **Discussion**
    - **Support**



# Acknowledgements

- **BAE SYSTEMS**
  - **MoD**
  - **WEAG**
  - **NEXUS**
  - **NATO**

# BAE SYSTEMS

## *The Advanced Technology Centre*

**The Advanced Technology Centres are involved in research, development and technology acquisition helping ensure BAE SYSTEMS remains a world leader in the defence and aerospace market.**

*Ayman El-Fatary*

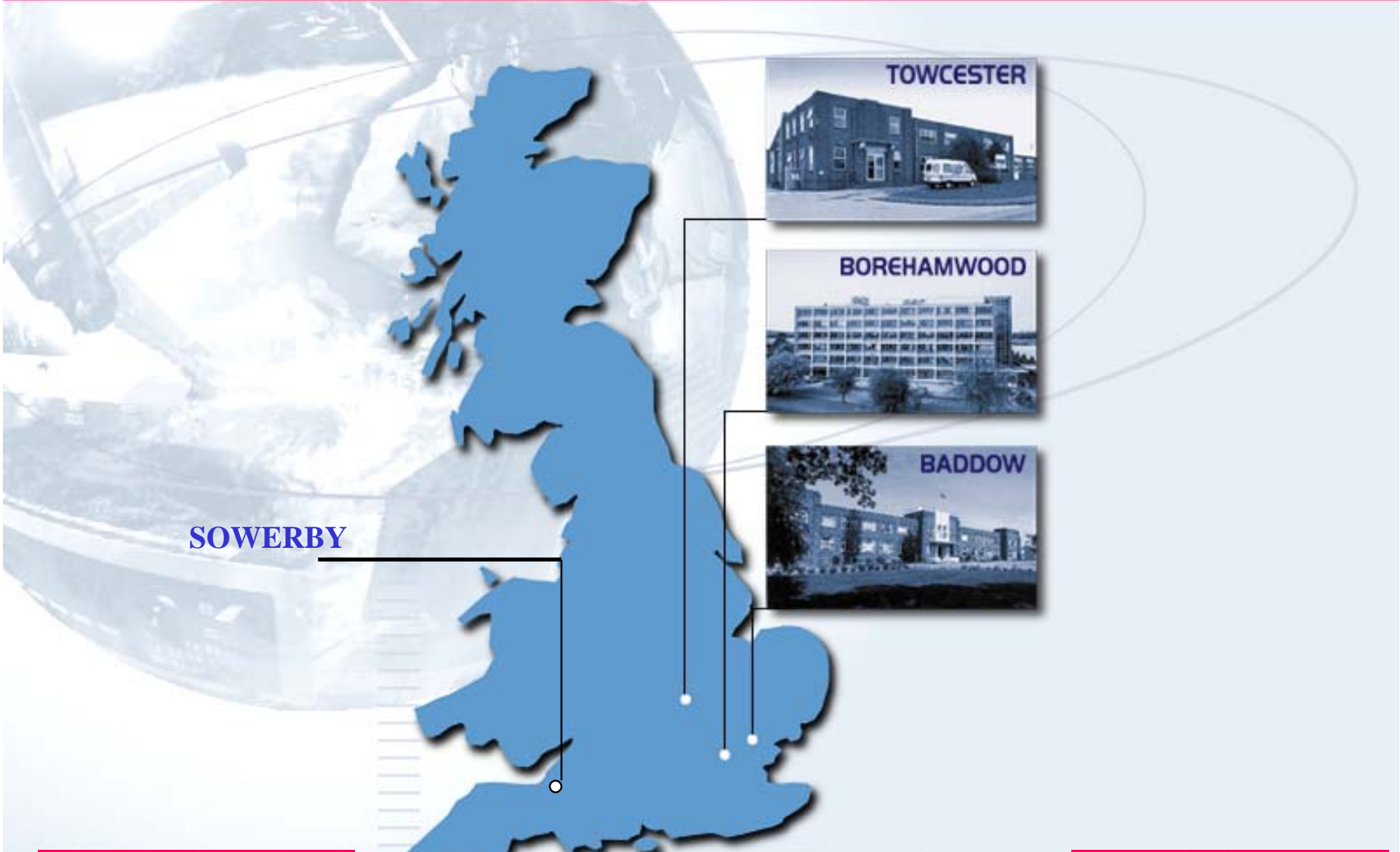
*Baddow*

*Borehamwood*

*Sowerby*

*Towcester*





**SOWERBY**

**BAE SYSTEMS**

*Advanced Technology Centre*

**BAE SYSTEMS**





# As for the presenter, ME !

**NAME:** Ayman El-Fatary



PII Redacted

**Education:** School (Cairo)  
Loughborough Univ. (BSc)  
Canterbury Univ. (PhD)

## Professional Career:

GEC's Hirst Research Centre (1978)  
re-named MRC, GMMT and, now BAE SYSTEMS'  
- ATC.

Currently, Head of Systems Department

## Expertise:

Optical Fibre systems, Optical techniques, Sensors & Biosensors  
Microsystems

**Interests / hobbies:** Art, music & Poetry

“Other” Interests: Red wine & .....





MEMS / MST

**Definitions !**



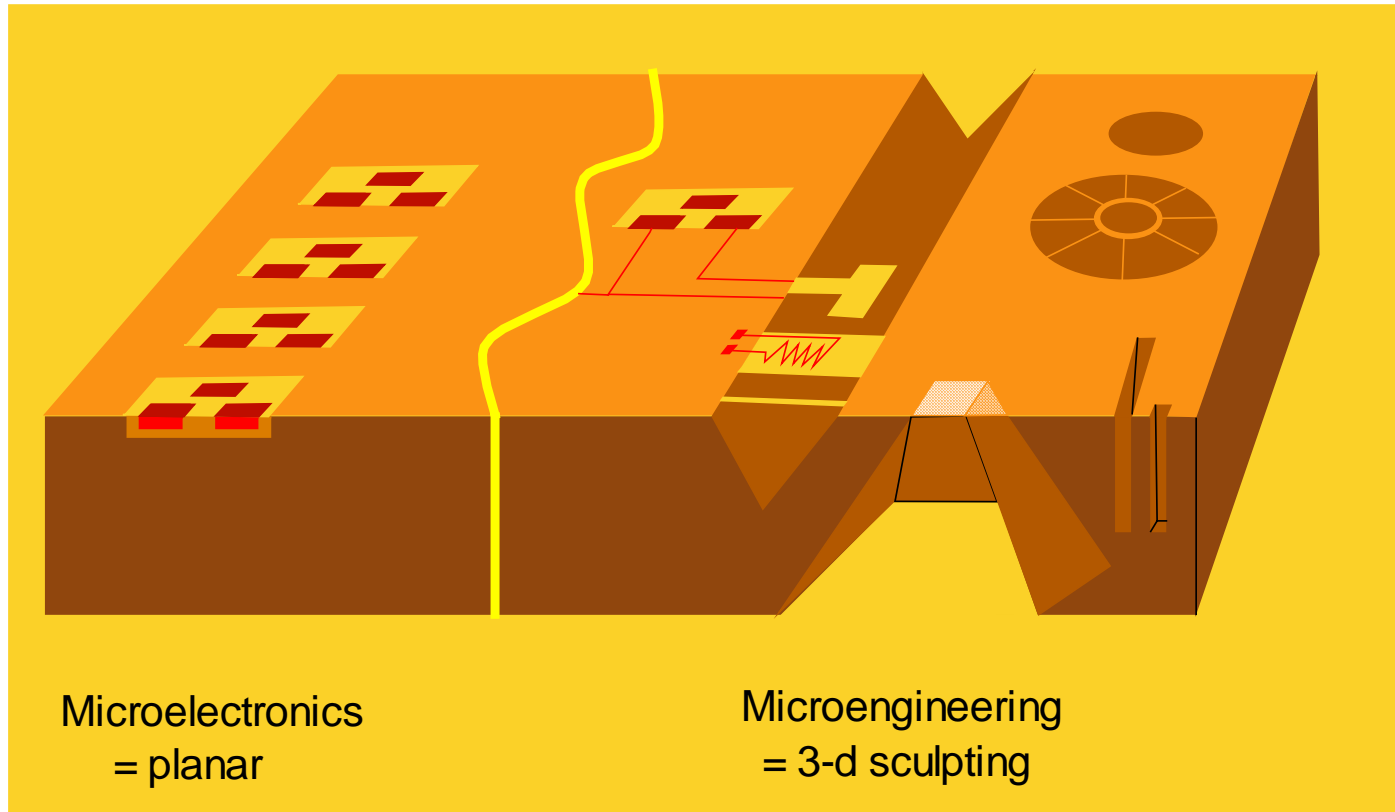


## A plethora of Acronyms !

- **MST**: European for Micro-System Technology (sensing + processing + actuation)
- **MEMS**: American for Micro-Electro-Mechanical-Systems (electrical + mechanical + IC compatible processing)
- **Micromachines**: Japanese for miniaturised factories / robots
- Also: **MOEMS** / **MEMtronics** / **ASIMS** and **μSystems**



# Differences between Micro-Electronics & Micro-Engineering





# Micro, Nano and MNT

**BAE SYSTEMS**

## - Positioning -

Feature Size

microns

1000

100

10

1

0.1

0.01

0.001

2000

2005

2010

2015

**Microsystems Technology**

**Micro-Nano Technology**

**Microelectronics /  
Nanoelectronics**

**Nano Technology**

**Molecular Science &  
Technology**

*TOP DOWN*

*BOTTOM UP*

Courtesy RAL



# Micro, Nano and MNT

## - *What is what* -

BAE SYSTEMS

### Microtechnology

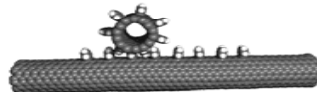
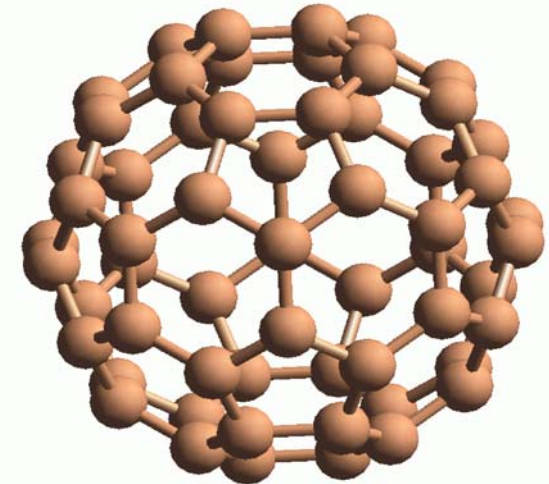
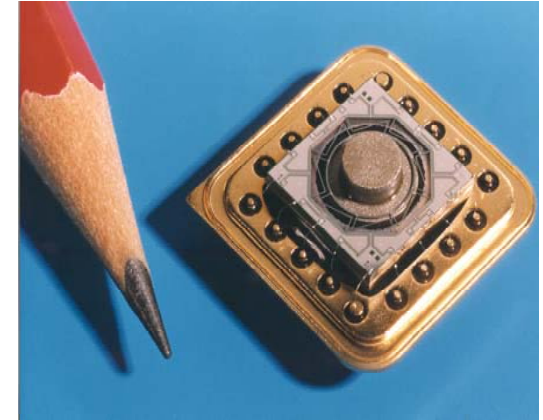
is the fabrication of millimetre sized devices with micron and nano-sized rules by bulk deposition and patterning millions of atoms in any part.

### Micro-Nano-Technology

is the use of the properties of micro and or nano-technology in micro and macro applications for further shrinking, integration and miniaturisation of sensing & actuating functions and for microsystems.

### Nano-Technology (Molecular T)

is the building up of structures or materials in an atom-for-atom specific way; every atom counts Theoretically anything could be built

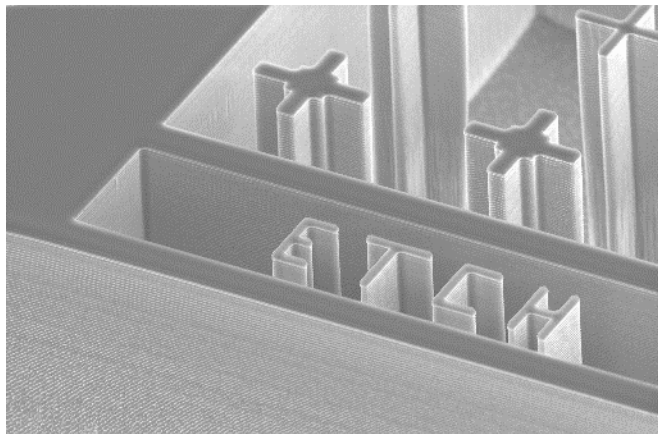




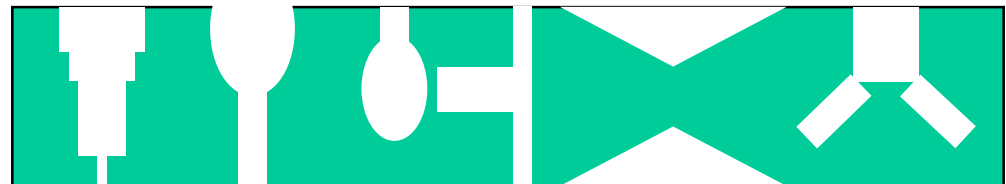
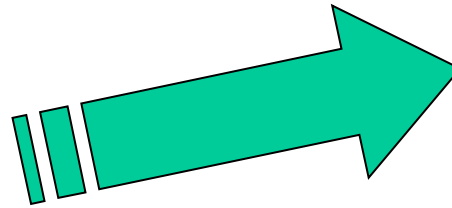
## Advanced fabrication techniques

- *Development of etching and bonding techniques*
- *Introduction of new equipment*

Facilitating the next steps in MEMS technology to provide improved design flexibility for future devices

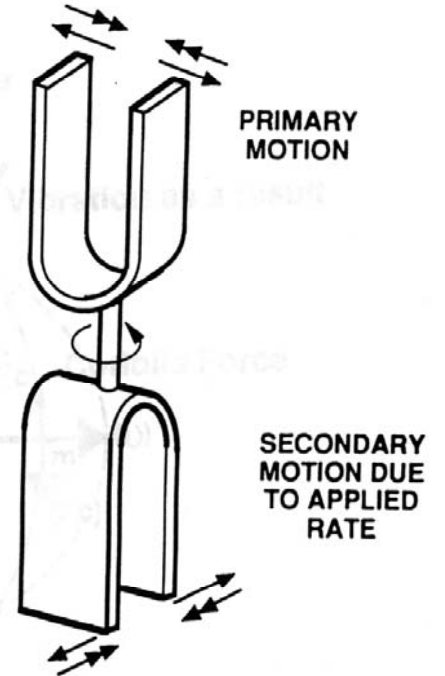


Present 2 1/2 D deep etch is limited to 'extrusion' in 3rd dimension



These proposed structures will lead to new or improved devices, eg miniature pneumatics thrusters, fuzing elements, actuators, motors etc

**BAE SYSTEMS**



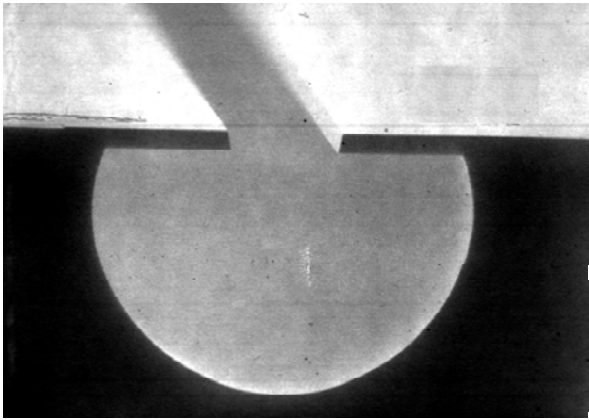
PRIMARY MOTION

SECONDARY MOTION DUE TO APPLIED RATE

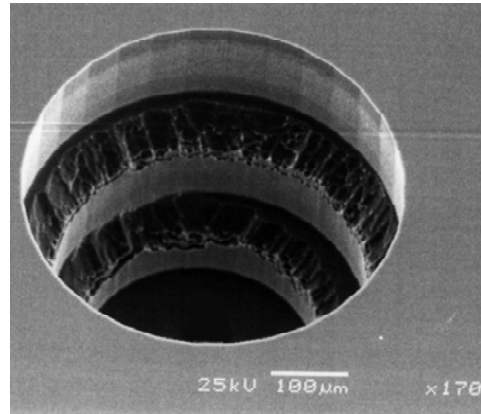


# Advanced fabrication progress

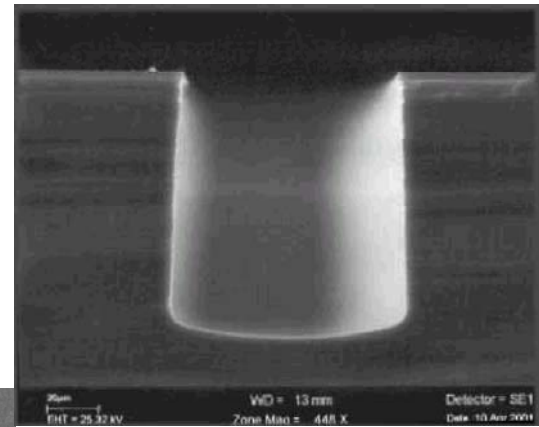
Some first attempts at profile control



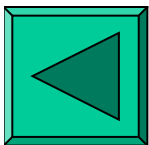
Isotropic etch



Sequential lithography



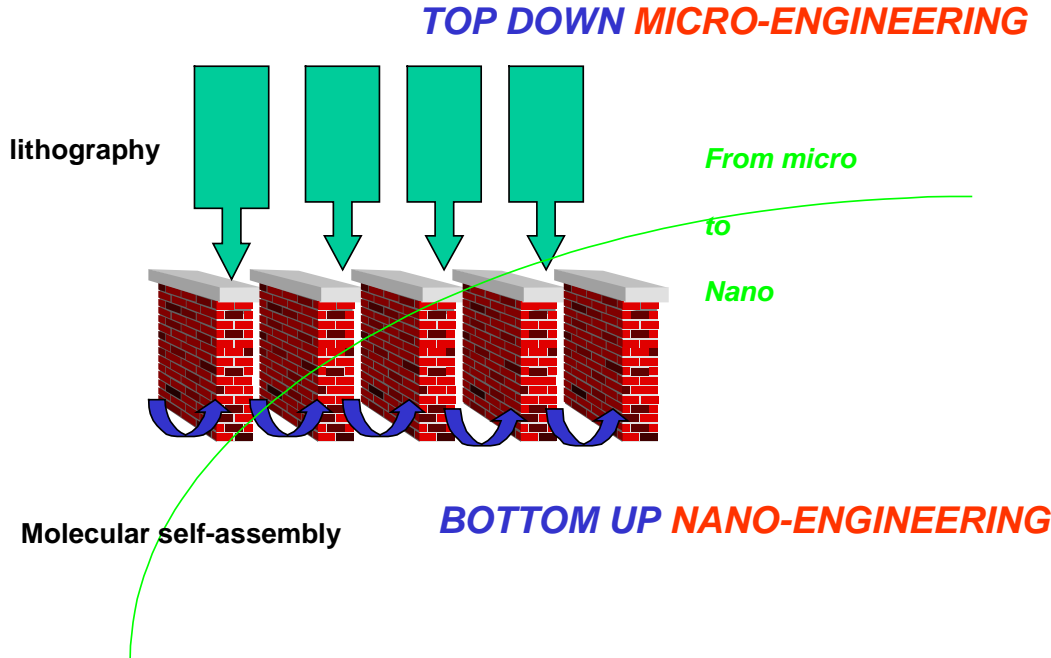
Deep reactive ion etch





# Nanotechnology - (yet another) **Definition**

**“A process for manipulating smallest natural structures (atoms & molecules) where Quantum mechanics rules.”**





# **MEMS / MST**

## **Advantages (proven & potential)**





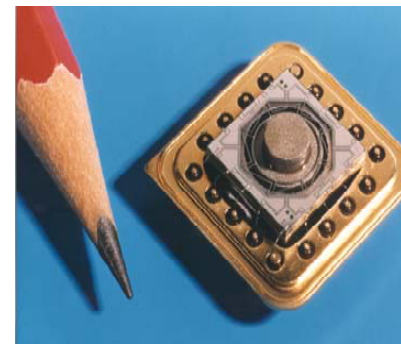
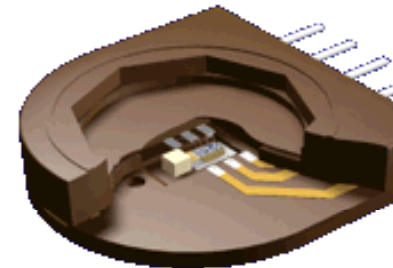
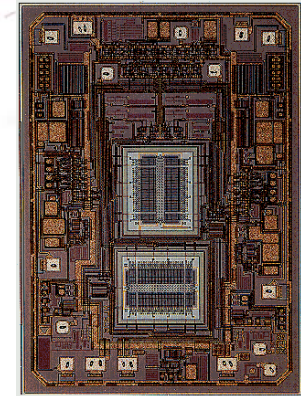
Sugar crystal  
ship  
on top of a  
pin-head

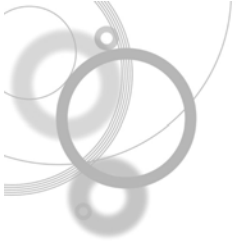
*“There’s no question that there is enough room on the head of a pin to put all of the Encyclopaedia Britannica” - Richard P Feynman, 1959*



## Potential Advantages of Micro-Engineered Devices

- Smaller size
- Lighter
- Cheaper
- Lower power
- Higher reliability
- Increased levels of integration (on board electronics, self test)
- Multi-functional (accel, yaw, temp and pressure)





# **The BRAMMS Project**

**A study of MEMS and Defence  
Applications**

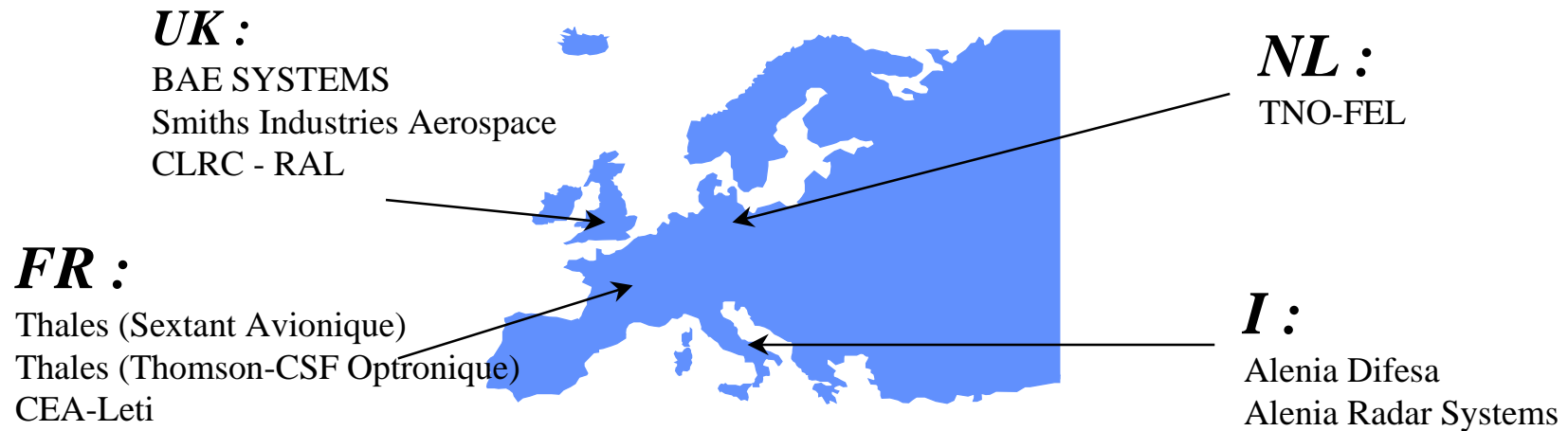
Western European Union (WEU)  
Western European Armaments Organisation (WEAO)  
Research Cell (WRC)

## *B.R.A.M.M.S.*

# *B*road *R*equirements for *A*dvanced *M*ilitary *M*icro-*S*ystems

A collaborative study for **RTP 2.30**

## Partners





# BRAMMS CONCLUSIONS

**MEMS / MST technologies will, it is foreseen, proliferate within the following main system-based applications:**

- **Inertial Systems for missile guidance & control**
- **Health monitoring systems**
- **Power management systems**
- **Displays (cockpit and helmet-mounted)**
- **Chemical & biological sensors**
- **Battlefield damage assessment and target identification systems.**



## *BRAMMS Conclusions - The hurdles*

- **Military MEMS will depend, heavily, on the commercial / civil MEMS developments.**
- **Low volumes, for the military markets, will attract high costs.**
- **Military product life-cycles exceed those for commercial / consumer products. Both process availability and product obsolescence become a major concern.**
- **Access to military-specific MEMS developments by the civil markets may have security implications.**
- **Repair of MEMS is not feasible. Diagnostics is difficult.**



## *Tough Requirements on MEMS !*

- **Typical specifications for military applications have been drawn:**

<b>Vibration:</b>	<b>20 to 2,000 Hz</b>
<b>Structural Resonance:</b>	<b>&gt; 2,000 Hz</b>
<b>Temperature:</b>	<b>-65°C to &gt; +125°C</b>
<b>Mechanical shock:</b>	<b>&gt;10,000 g</b>
<b>Angular Acceleration:</b>	<b>&gt;500,000 rad/S<sup>2</sup></b>



# **The BRAMMS Project**

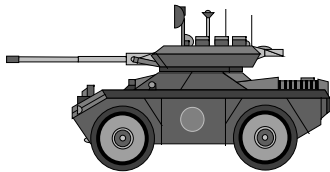
## **Defence Applications**





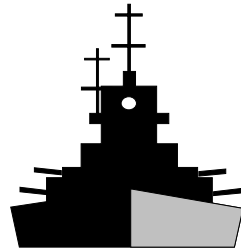
# Military MEMS/MST ; Main Applications

## LAND



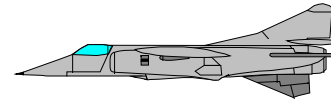
- Smart & Competent Munitions.
- Gun Launched Munitions
- Communication Systems
- Soldier / Combatant Equipment
- Surveillance Systems

## SEA



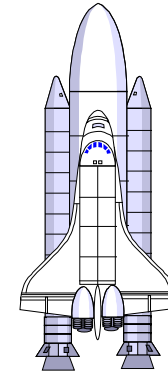
- Torpedo Control
- Communication Systems
- Platform Stabilisation & Control Systems

## AIR



- Aircraft Platform Control Systems
- Avionics & Flight Control
- Equipment Monitoring & Failure Prediction
- Communication Systems
- Combat Systems

## SPACE



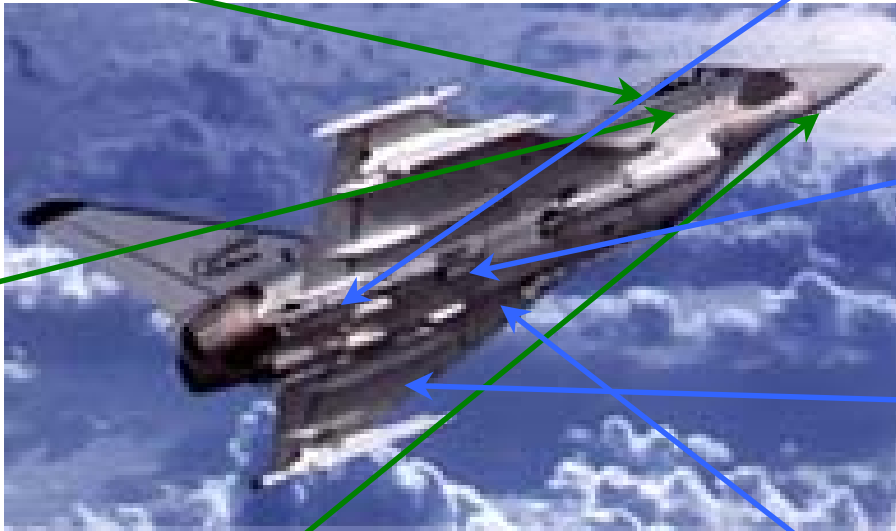
- Guidance & Control
- Communication Systems

# Future MEMS applications for Military aircraft

**BAE SYSTEMS**

**Navigation & attitude**  
**Radar**  
Air Data, Instruments,  
Flight Control,  
GPS receiver & antennas  
Inertial Measurements Units

**Man machine interfaces**  
Displays, Head up Displays  
Sighting, Integrated helmet  
 $\mu$ IMU Standby Instruments



**Engine & reactors**  
FADEC  
Hydraulics

**Energy management**  
Generation monitoring  
Pressure, Humidity..

**Structure monitoring**  
Stabilisation  
Vibrations  
Structure fatigue  
Smart skin

**Landing systems**  
Hydraulic pressure  
Tyre pressure, etc..

**Navigation Optronics**  
Radar, FLIR,  
reconnaissance sensors

**Mission Optronics & electronics**  
target detection  
E.O. missile guidance  
E.O.C.M.  
I.F.F systems



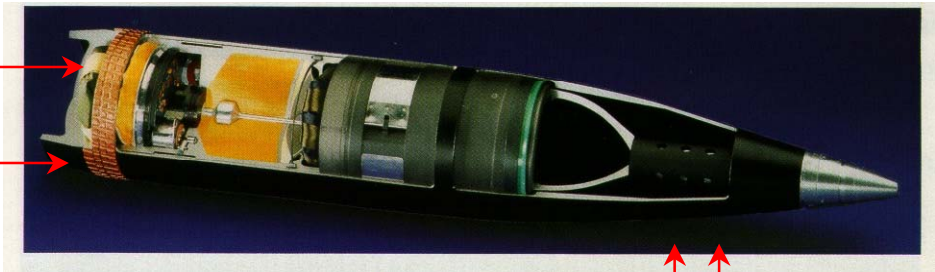
# FUTURE MEMS APPLICATIONS FOR SMART AMMUNITIONS

**BAE SYSTEMS**



SMART SURFACES

IMU/GPS CONTROL UNIT



GUIDANCE LINK

FLOW AND PRESSURE CONTROL

SAFING AND ARMING

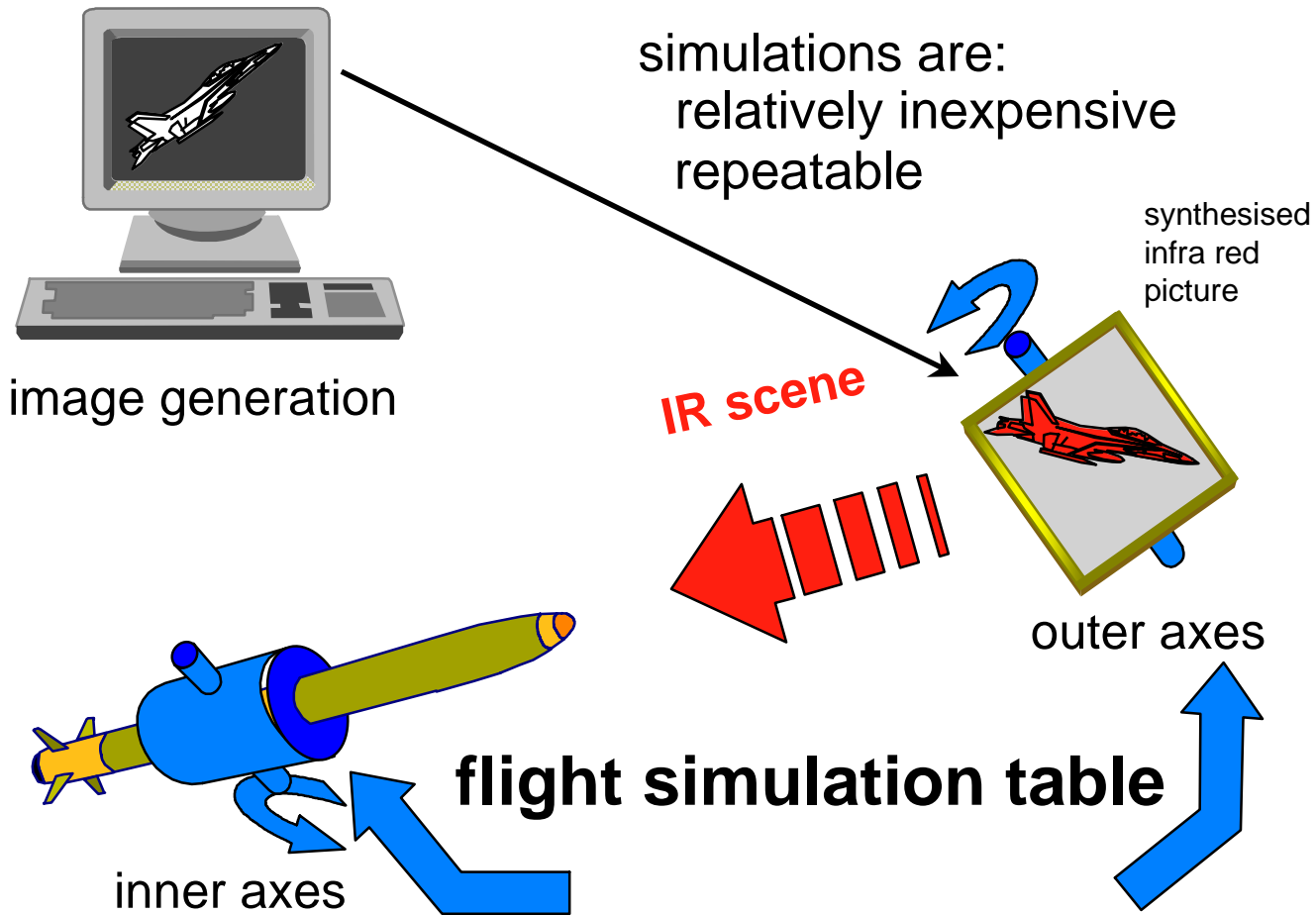
FUZE AND SIGNAL PROCESSING



MEMS subsystems and Components	Military systems									
	Smart Munitions	MicroUAV	Aircraft	Rotary wing Aircraft	Missile	Land Vehicle	Ships&Boat	Space Vehicle	Soldier Systems	Ground Systems
μIMU	•	•	•	•	•	•	•	•	•	
ISIS			•	•		•	•	•	•	
Three axis vibration measurement Unit			•	•		•	•	•		
μActuator for flight control	•	•	•		•			•		
RF Communications front end	•	•	•	•	•	•	•	•	•	•
HUMs		•	•	•	•	•	•	•		•
Power management Systems		•	•	•		•	•	•	•	•
Fast Scanners	•	•	•	•	•	•	•	•	•	•
Compass and vertical axis measurement unit		•	•	•		•	•	•	•	•
Active vibration control		•	•	•	•			•		
Biochemical Sensors		•	•	•		•	•		•	•



# Thermal Picture Synthesiser (TPS) - Infra red missile development and proving



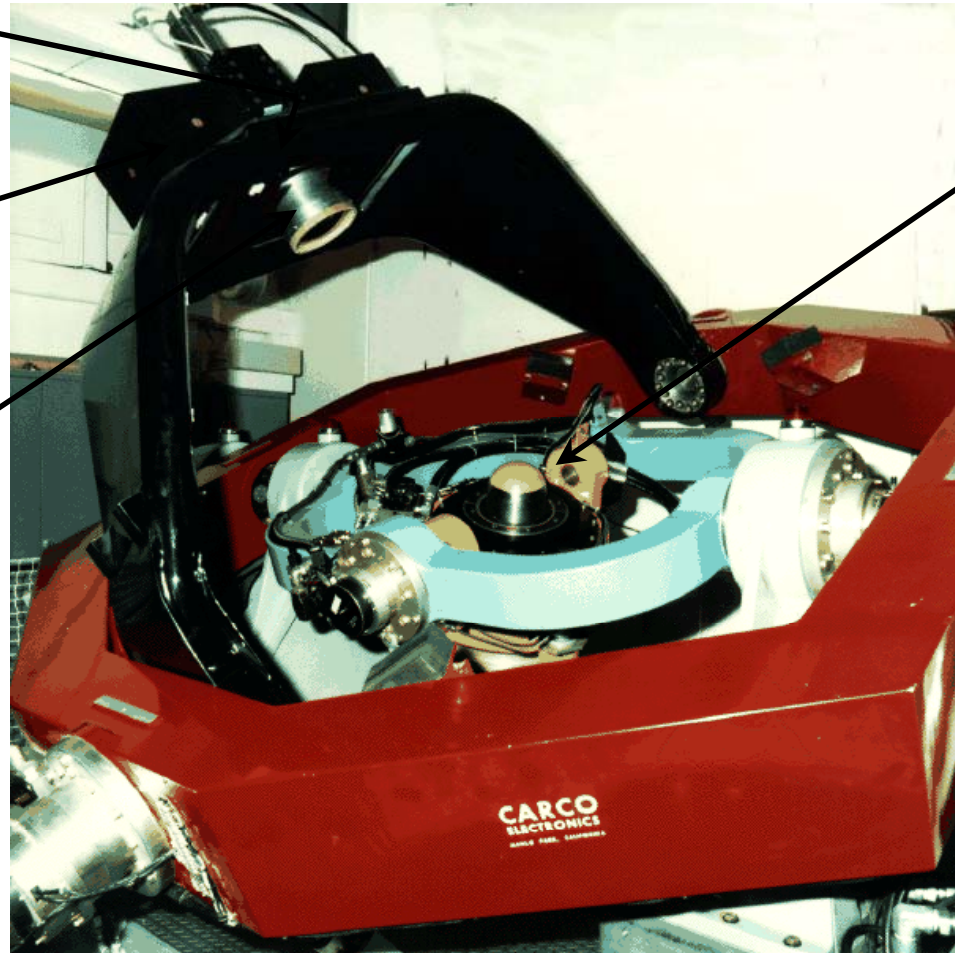


## TPS System on Flight Table

**TPS Wafer**

**TPS Control Electronics**

**TPS Collimating Optics**



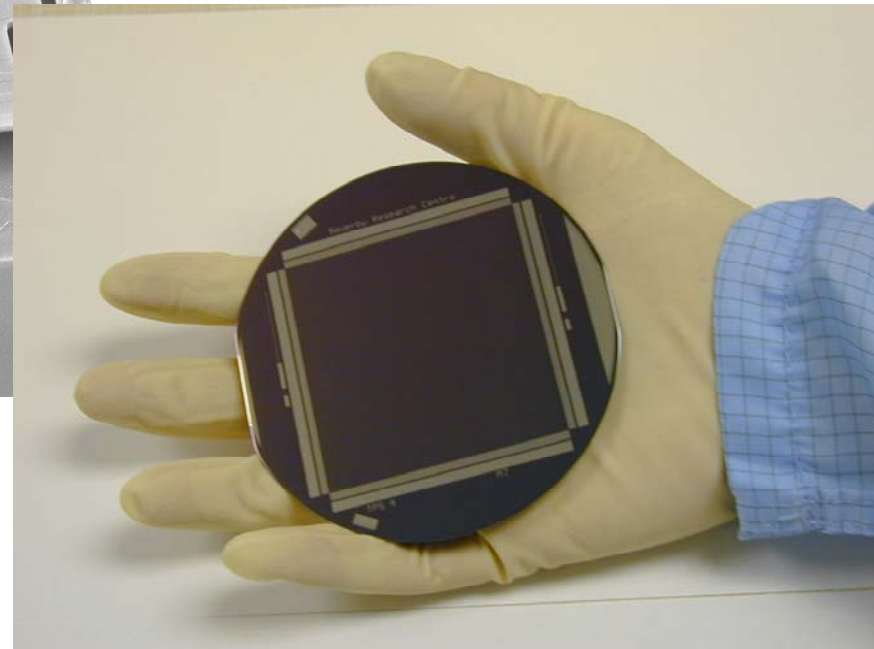
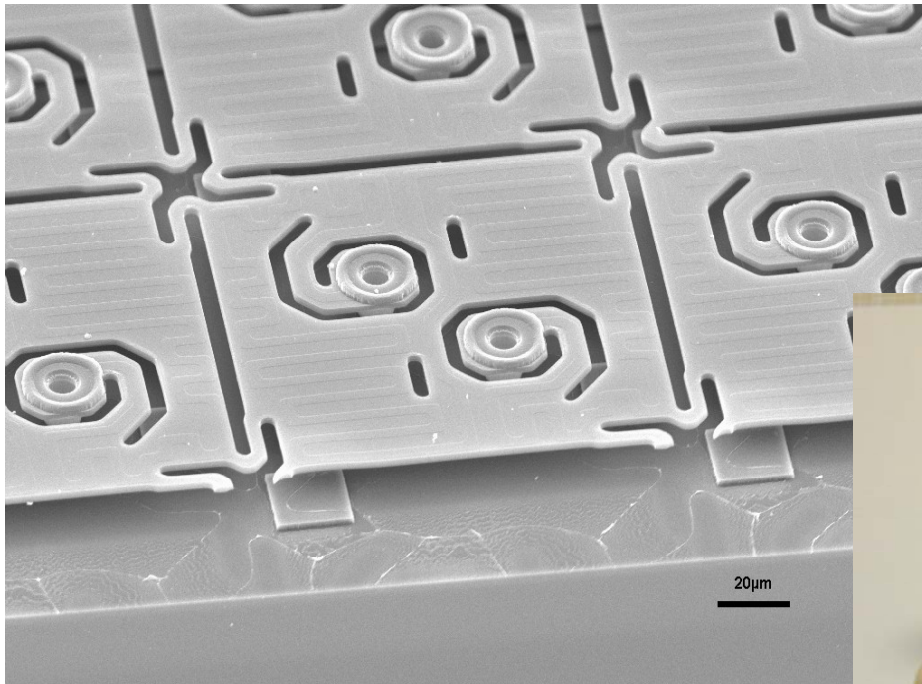
**IR Seeker**





## ***TPS Pixel detail***

**BAE SYSTEMS**



***TPS 5 'chip' on 100mm wafer***

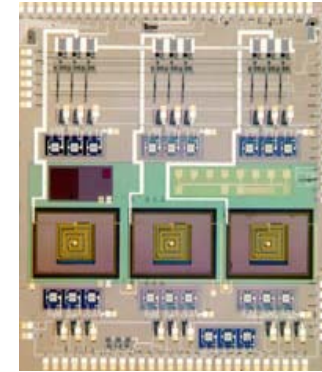


# Aerodynamic Applications of MEMS - Flow Control Possibilities

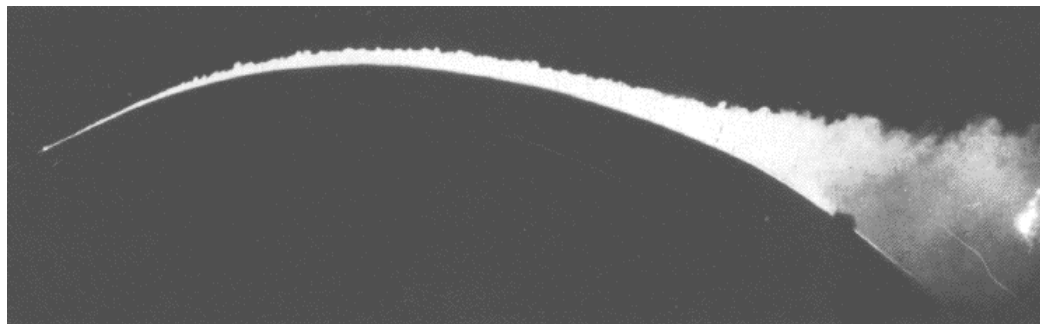
BAE SYSTEMS



Vortex Control



Skin Friction Drag Reduction



Separation Control

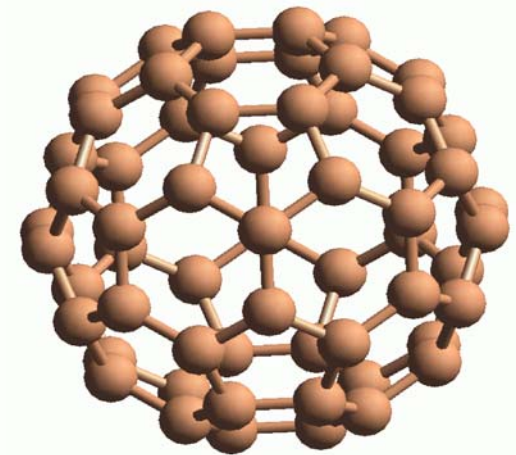




## Francis Crick 1916 British molecular biologist

*Almost all aspects of life are engineered at the molecular level, and without understanding molecules we can only have a very sketchy understanding of life itself.*

*What Mad Pursuit (1988) ch. 5*





**BAE SYSTEMS**





# MEMS Aerospace Applications

## *Les Applications Aérospatiales des MEMS*

An AVT-105 Lecture Series No. 235

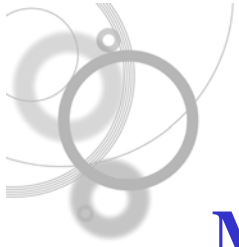
organised by the

Applied Vehicle Technology Panel

*Part 2*

*Accelerometers*





# **MEMS Accelerometers - Example Applications**

- **Automotive**
  - Airbags
  - ABS
  - Suspension
  - Tilt
- **Medical**
  - Pacemakers
- **Consumer**
  - Security
  - Smart homes
- **Industrial**
  - Noise & Vibration monitoring / control
- **Aerospace**
  - Navigation & IMUs

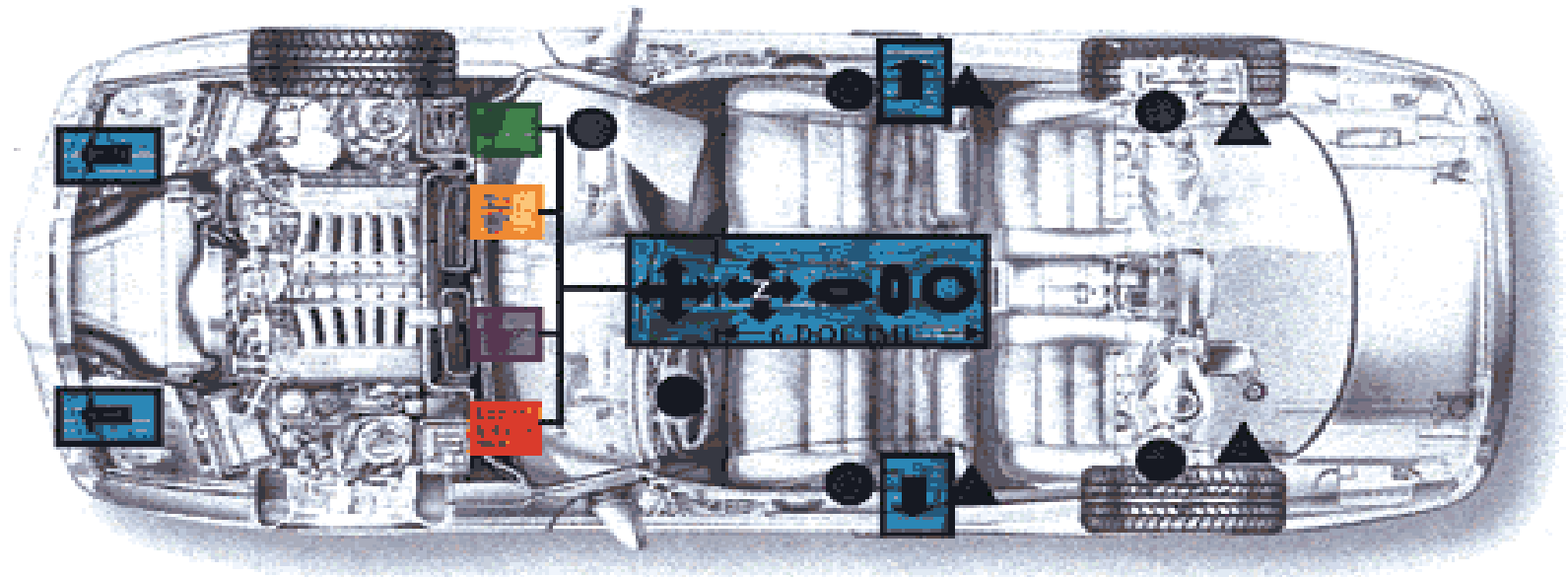






# Accelerometers for:




- **TILT or INCLINATION:** static acceleration driven by the Earth's gravity force (1g).
  - Car Alarms (motion detection)
  - Patient monitoring
- **INERTIAL FORCES:** velocity, distance or force (2g - 50g).
  - Airbag sensors
  - Navigation systems
- **SHOCK & VIBRATION** (2g - 50g)
  - Machinery health & condition monitoring
  - Event monitoring
  - Earthquakes



# Automotive Sensors

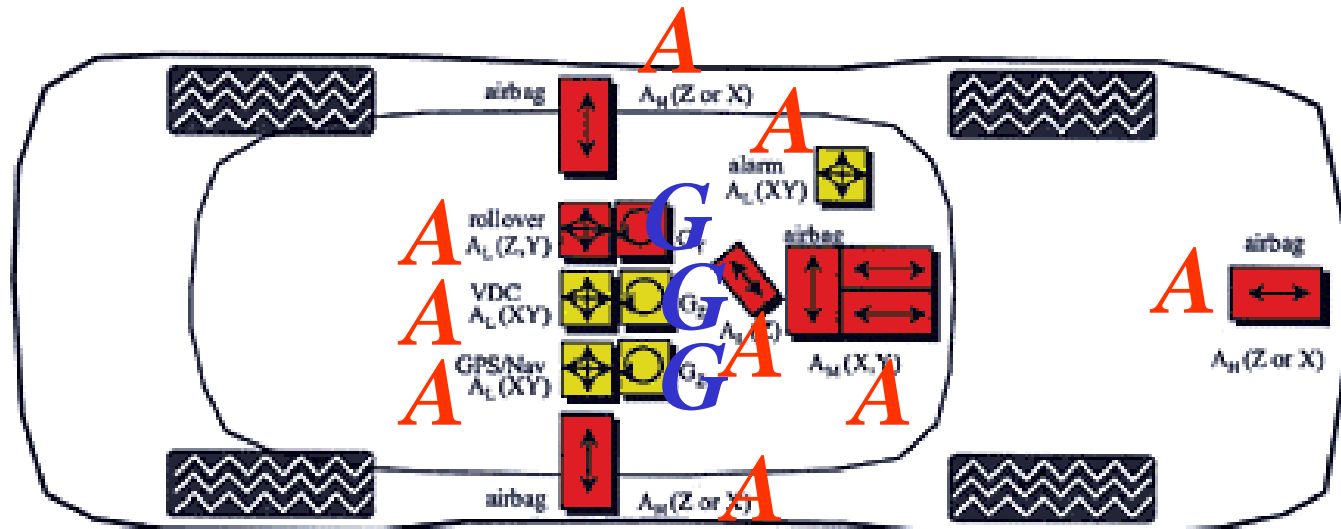


-  *Crash Detection System*
-  *Vehicle Dynamic Control System*
-  *Navigation Information System*
-  *Body / Chassis Control System*

-  *Satellite Sensor*
-  *Airbag*
-  *Seatbelt Sensor*



# Accelerometers & Gyros in Vehicles





**Legend**

G = Gyro

A = Acceleration

- L = low (<5g)
- M = medium (50g)
- H = high (>100g)

 Airbag system

 Non-Airbag system



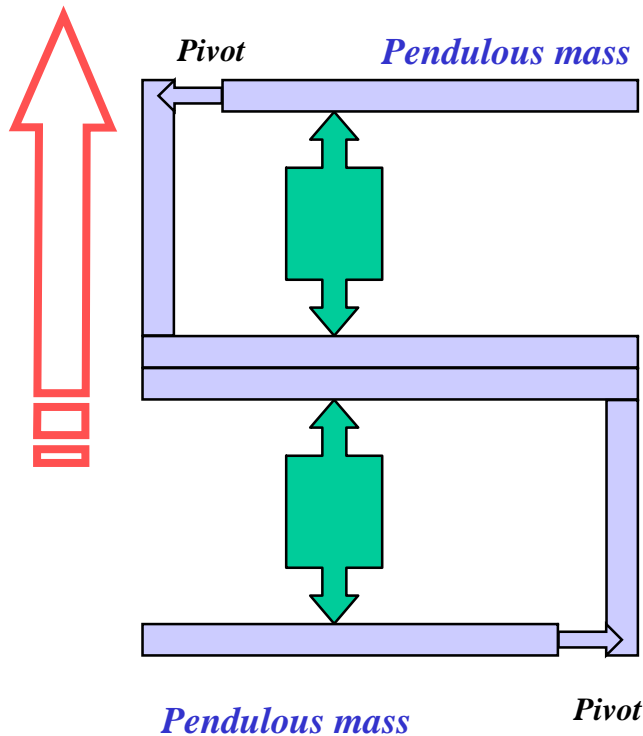


# Vibrating Beam Accelerometer

BAE SYSTEMS

$$\text{Acceleration} = f(F2 - F1)$$

ACCELERATION  
SENSING AXIS



*Beam under compression*

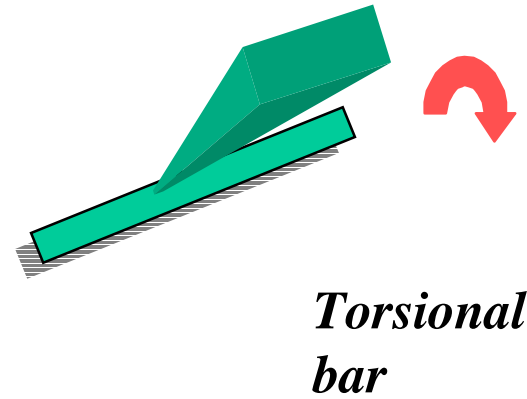
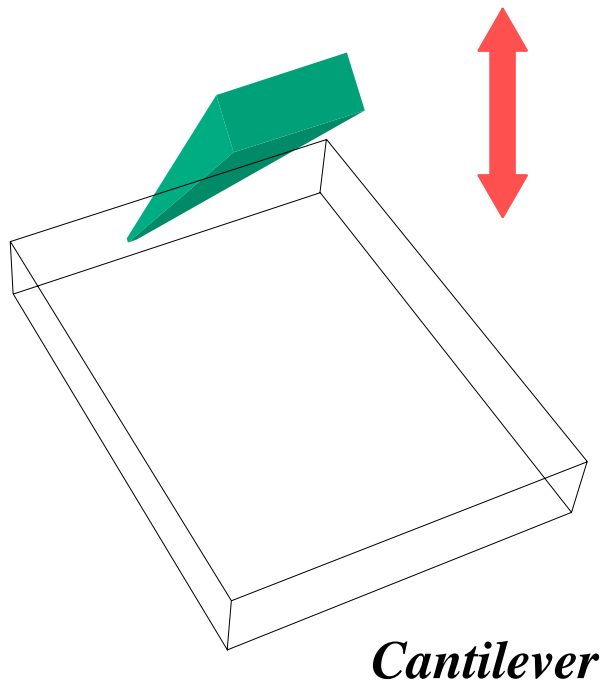
*Resonant frequency F2 (decreases)*

*Resonant frequency F1 (increases)*

*Beam under tension*



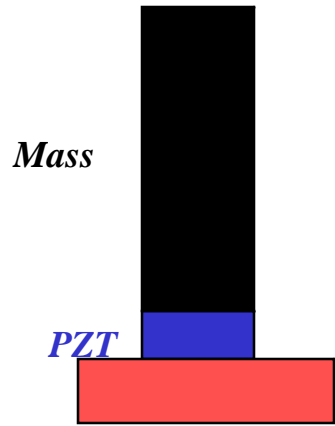
# Bulk Accelerometers



*Bridge structures*

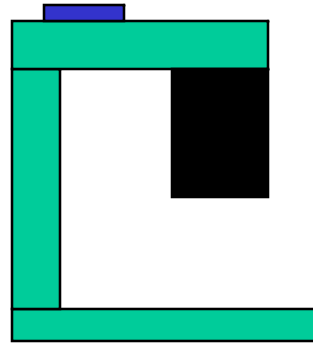


# (some) Detection Techniques

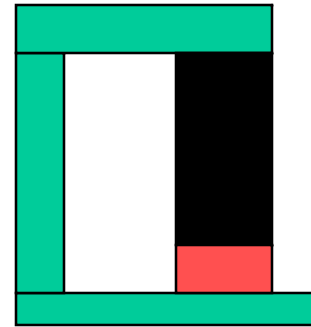


*Piezo-Electric*

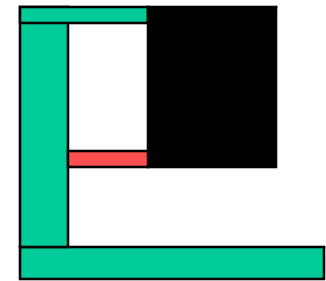
*PZT Strain gauge*



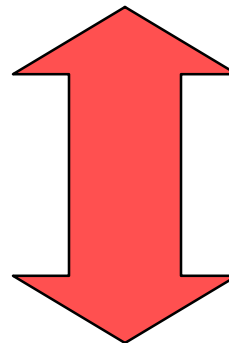
*Piezo-Resistive*



*Capacitive*



*Resonance*

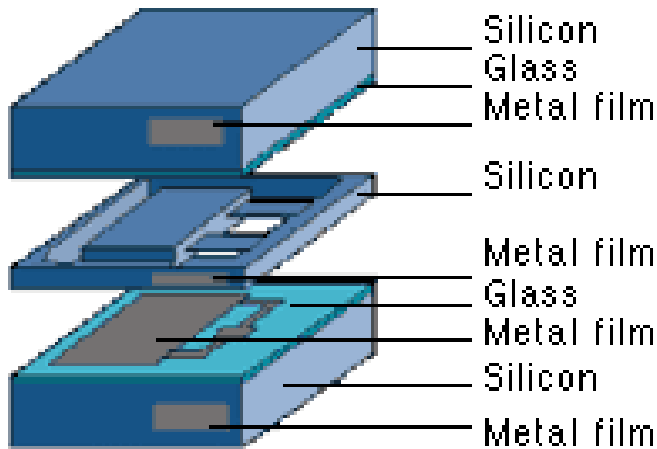


*Acceleration*



# Bulk Capacitive Accelerometer

## VTI Technologies

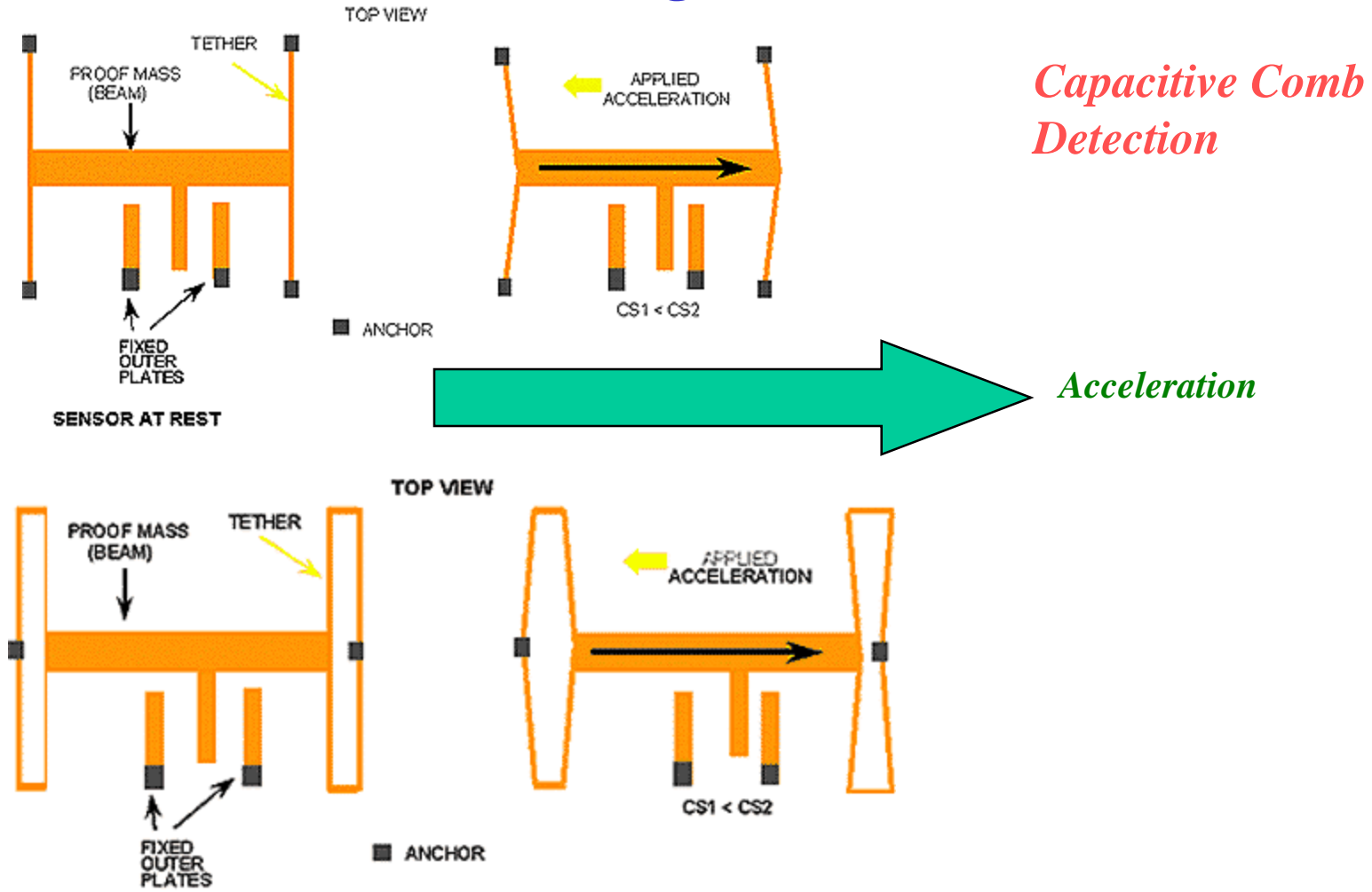


*Sandwiched Silicon bends with force and changes capacitance*



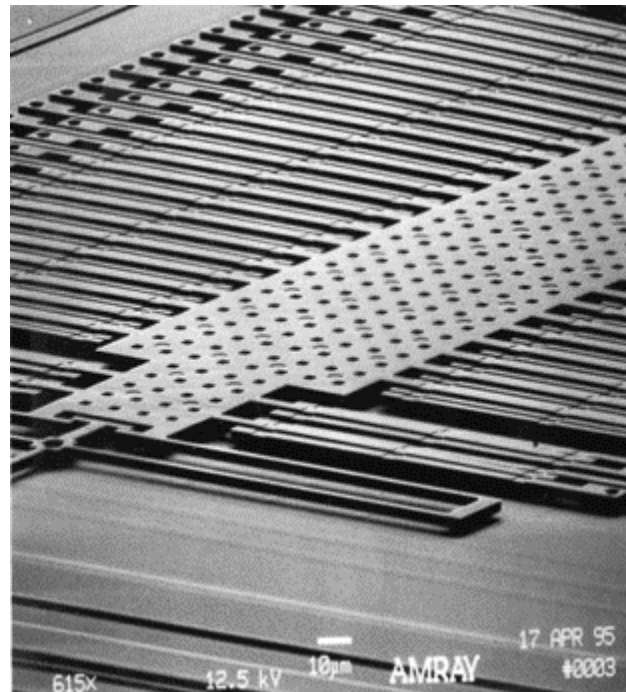
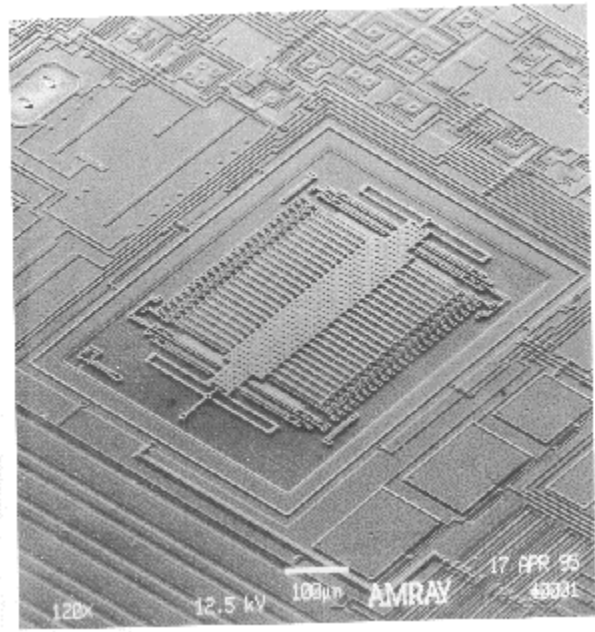
# Surface Micromachined Capacitive Accelerometers

## Analog Devices





*Surface Micromachined Capacitive Combs from Analog Devices*

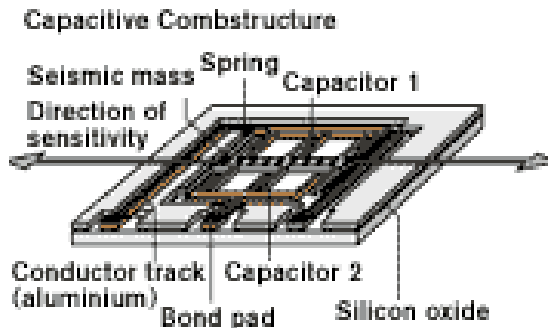


**Figure 6. iMEMS accelerometer in surface mount package**

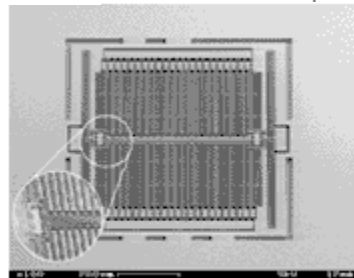
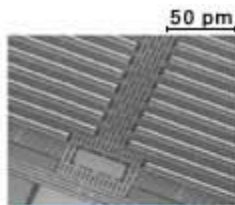
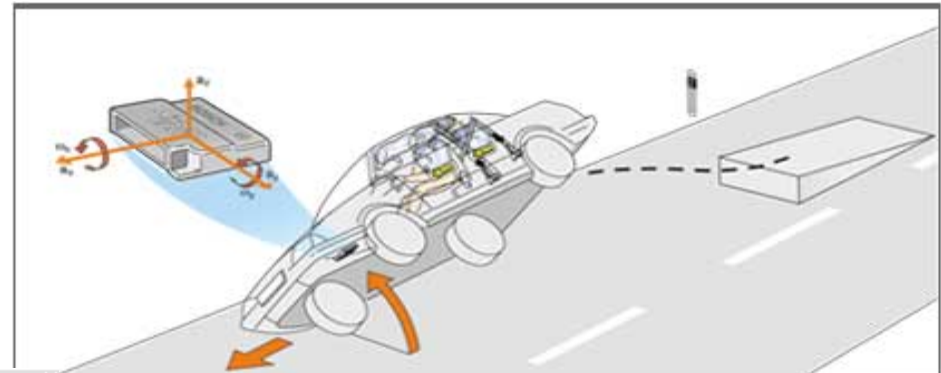


# Surface Micromachined Capacitive Accelerometers

## Robert Bosch GmbH



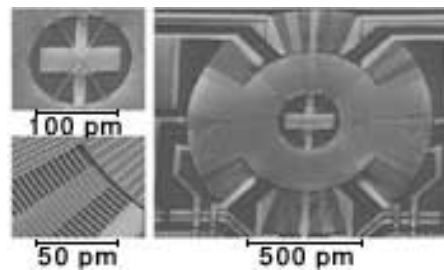
Functional principle



Surface micromachined sensor element



SMD Packaging PLCC 28



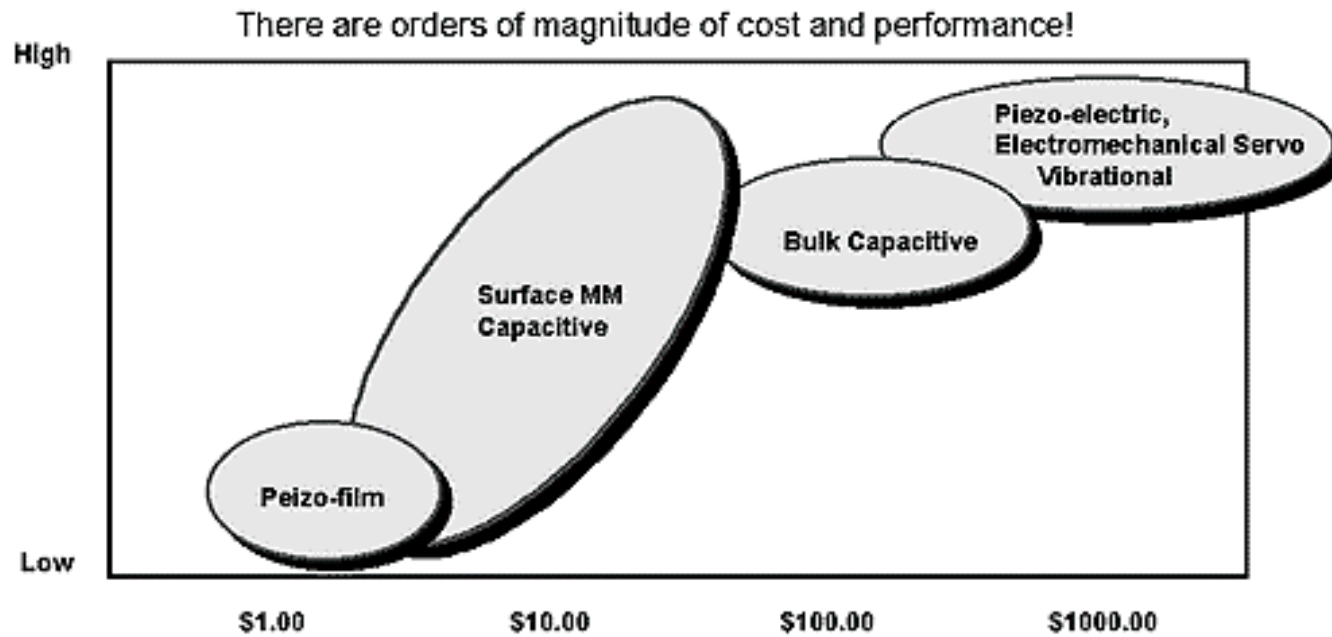
- Rollover Sensors*
- Front Airbag Sensors*
- Side Impact/Upfront Sensors*
- Anti-Lock Braking*
- Vehicle Dynamics Control*
- Headlight Levelling Systems*
- Navigation*
- Car Alarms*
- Virtual Horizon*



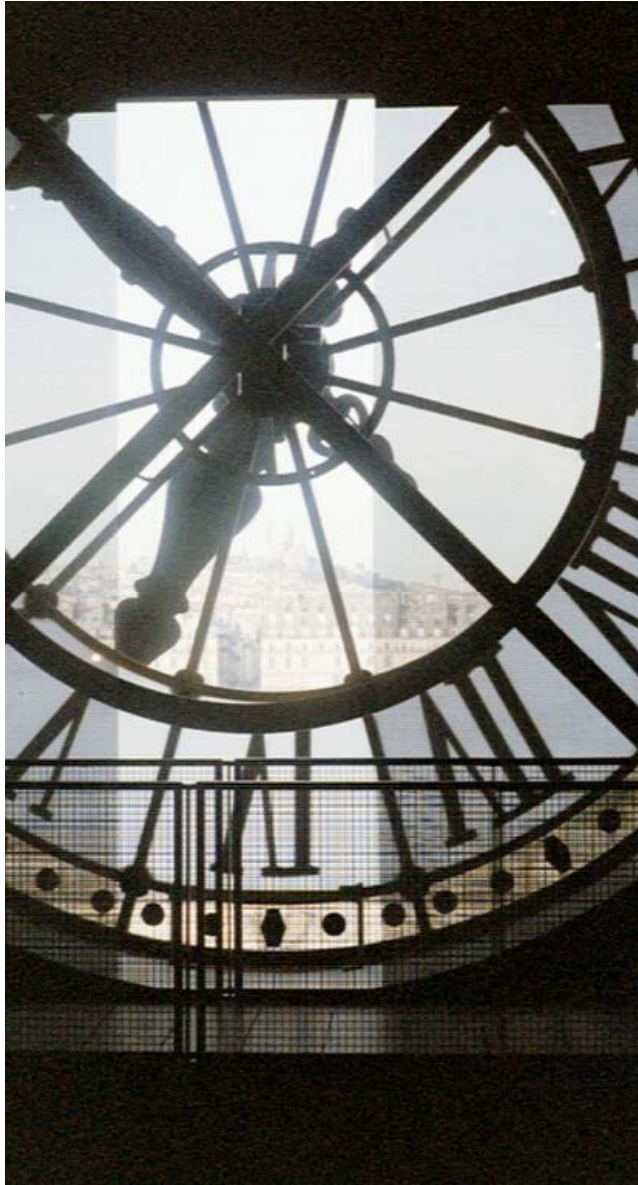
# Comparative Characteristics

	<b>Capacitive</b>	<b>Piezoelectric</b>	<b>Piezo-resistive</b>
<b>Impedance</b>	High	High	Low
<b>Size</b>	Medium	Small	Medium
<b>Temperature Range</b>	Very wide	Wide	Medium
<b>Linearity</b>	High	Medium	Low
<b>Sensitivity</b>	High	Medium	Medium
<b>Cost</b>	Medium	High	Low





*Performance Vs Cost (Analog Devices information)*



**BAE SYSTEMS**



# MEMS Aerospace Applications

## *Les Applications Aérospatiales des MEMS*

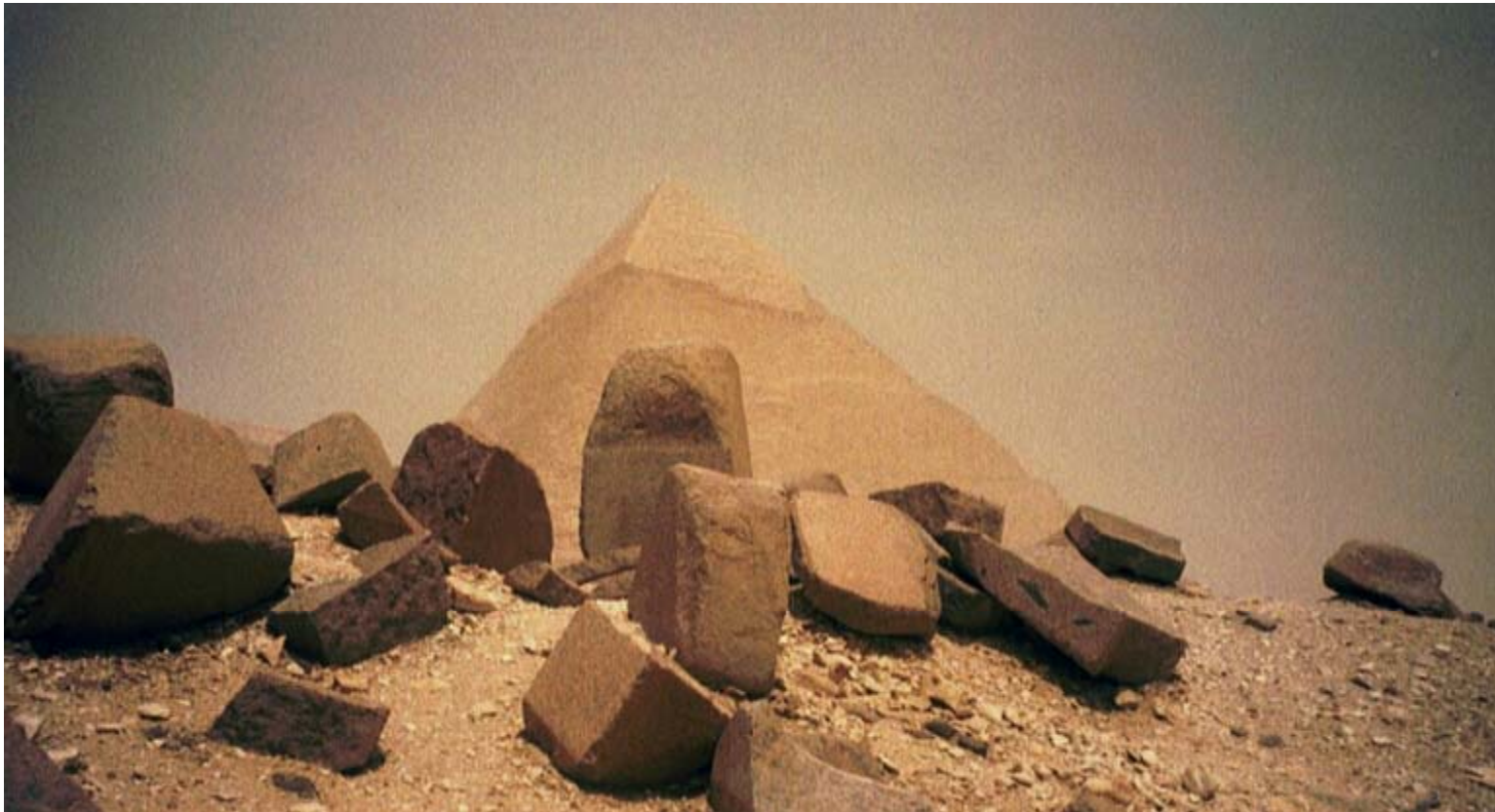
An AVT-105 Lecture Series No. 235

organised by the

Applied Vehicle Technology Panel

*Part 2*

*Gyros*





## Gyroscopes ?

- **Measures rotational values (speed of rotation / rates)**
- **degree per second ( $^{\circ}/\text{sec}$  or  $^{\circ}/\text{h}$ )**
- **Mechanical or Optical**
- **Accuracy and performance judged by:**
  - **Bias ( $^{\circ}/\text{sec}$  or  $^{\circ}/\text{h}$ ) = offset error output when sensor is static**
  - **Scale factor error (% of full scale) = linear deviation from true rate**
  - **Noise = drift and background/non-deterministic behaviour**

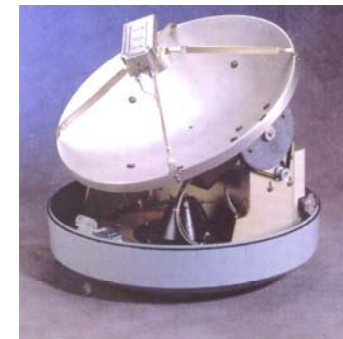
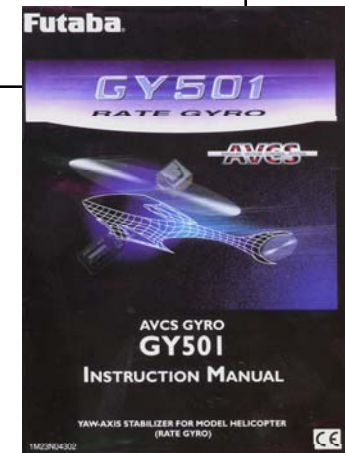
## Applications - Defence & Aerospace

- **Missile guidance**
- **Smart shells / guided projectiles**
- **Antenna stabilisation**
- **Unmanned Airborne Vehicles**
- **Flight Instrumentation and Training Pod**
- **Back-up flight instrumentation**



## Applications - Commercial

- Antenna Stabilisation
- Marine Autohelms
- Adult Toys - Futaba model helicopter, Sony pet dog
- Personal Navigators - (with GPS)
- IMUs - tracking systems, 3D computer mouse, orthopaedic
- Wheelchairs
- Racing Cars





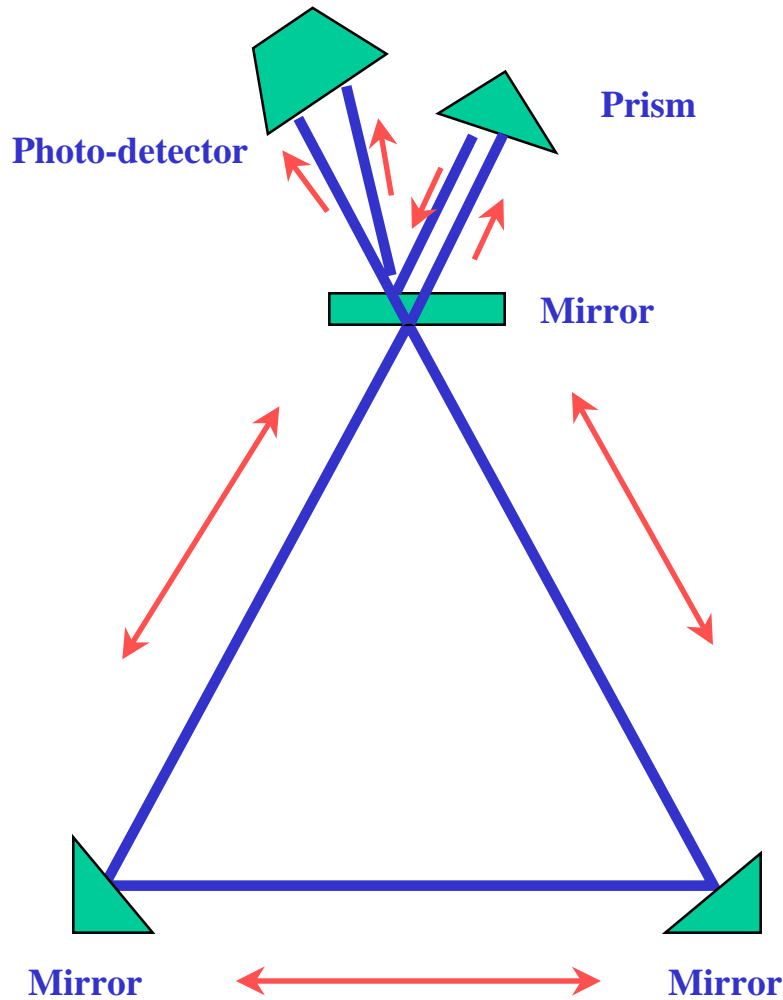
## Applications - Automotive

- **Advanced Braking Systems**
- **Navigation**
- **Rollover Protection**
- **Autonomous Cruise Control**
- **Headlamp Steering**





# Laser Gyros



*Fringe angle change*

$$\Delta \Phi = [ (8 \pi A) / \lambda L ] \Delta \theta$$

*Integrated rate input angle change*

*A = Area enclosed by the laser beam*

*L = Length of laser beam path / perimeter*

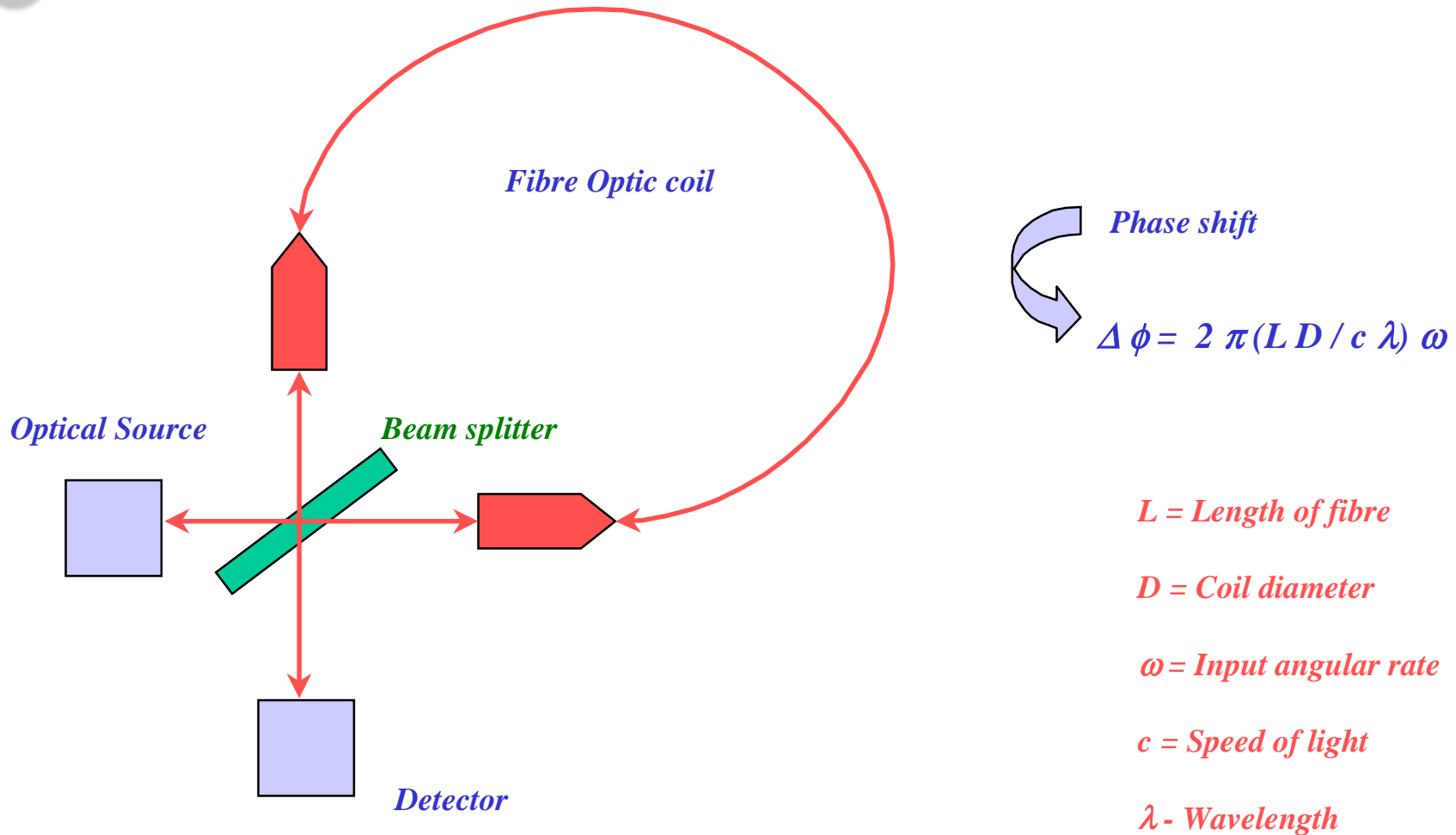
*$\lambda$  = Laser wavelength*

*Sagnac Effect: difference in transit time between two light waves propagating through the same path in opposite directions*



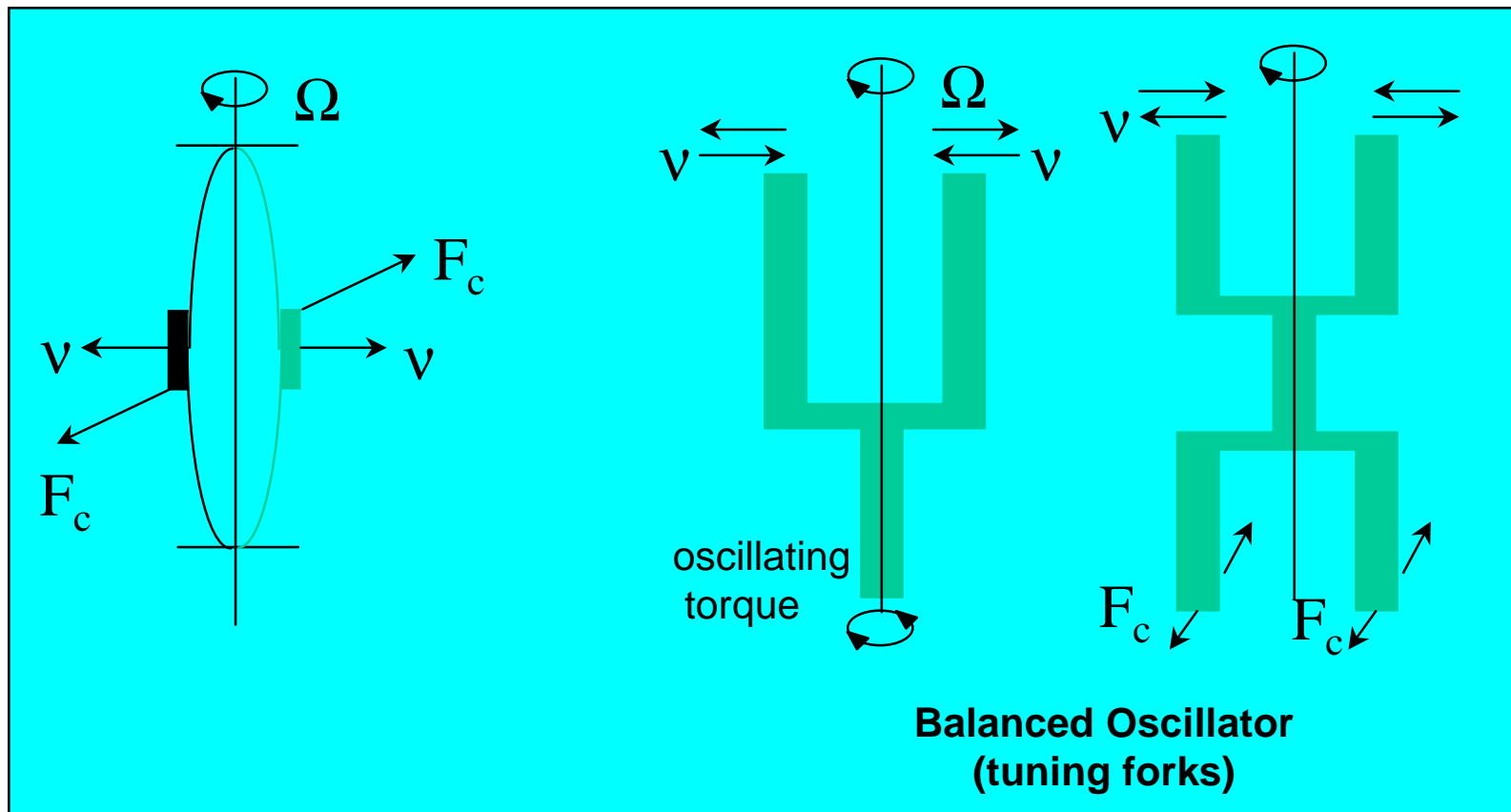
# Fibre Optic Rate Sensors

BAE SYSTEMS



**Sagnac Effect:** *difference in transit time between two light waves propagating through the same path in opposite directions*

# Simple Oscillator Gyros



*The vibration of the tuning fork, whilst rotating, creates Coriolis acceleration*

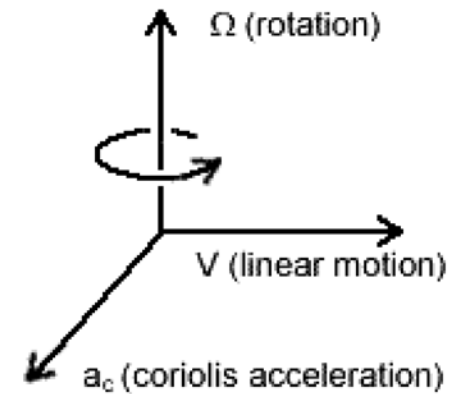


# Tuning Fork / Vibration Gyros

## The Coriolis Effect

All vibrating gyroscopes rely on the Coriolis acceleration. This acceleration is experienced by a particle undergoing linear motion in a rotating frame of reference, where the rotation axis is perpendicular to that of the linear motion.

The resulting acceleration, which is directly proportional to the rate of turn, occurs in the third axis, perpendicular to the other two axes.

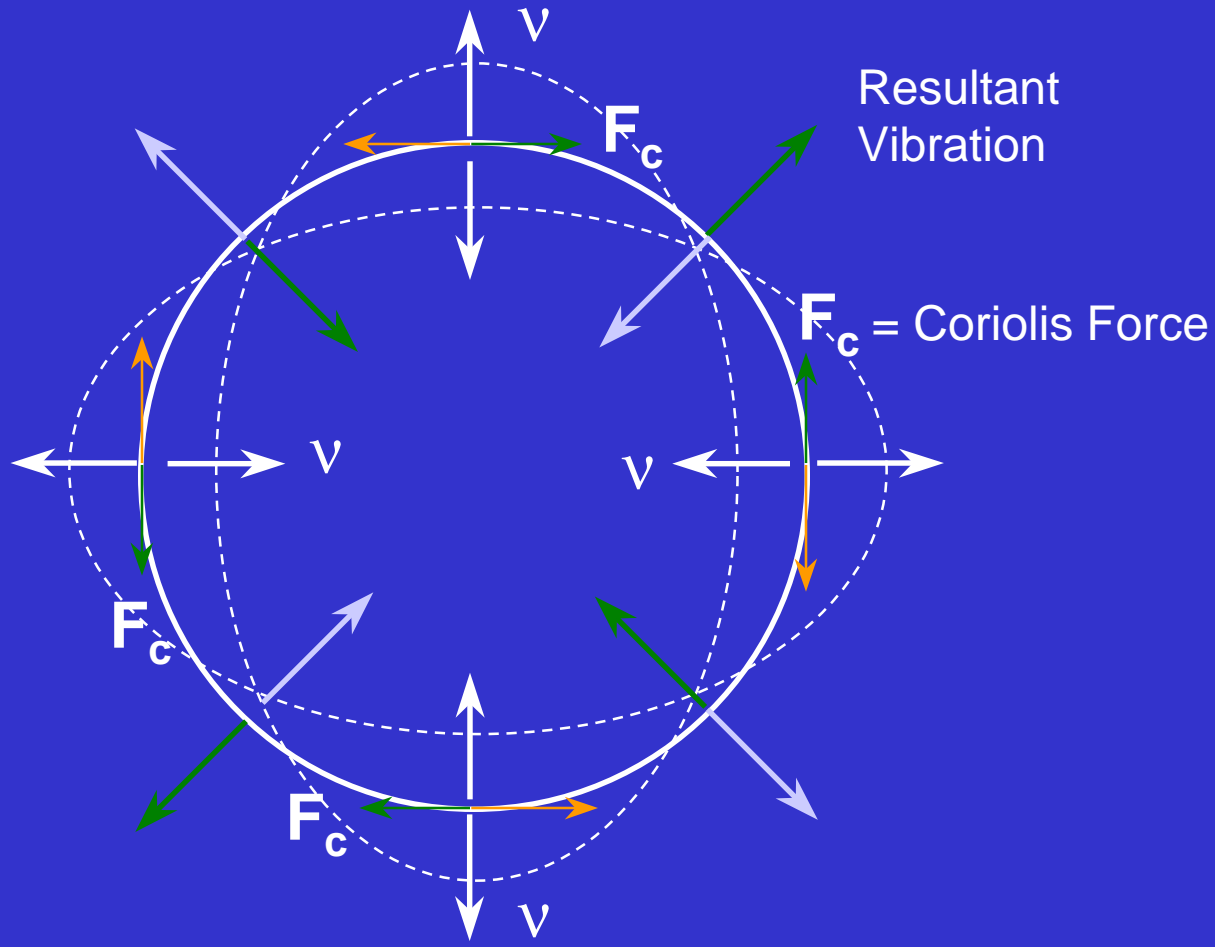


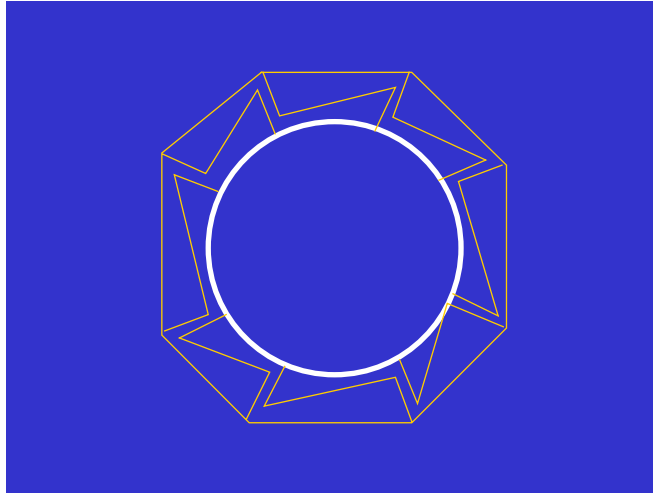


# Coriolis in Gyros

- **Reminder - the coriolis force causes the rotation (acceleration) from linear motion in a rotating frame**
- **Acceleration force is proportional to the rotation rate**
- **In a gyro, linear motion is the vibration mode in a solid body**
- **Under rotation, energy is coupled from one vibration mode to another**
- **The magnitude of the vibration in this second mode defines the rotation rate sensed by the gyro**

# Balanced Shell Resonator Gyro (SiVSG)





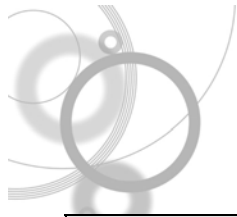
## Coriolis Explained/Demonstrated

- **Linear motion in a rotating frame**
- **Ball's motion is linear with respect to the playground**
- **Ball's motion is curved with respect to the roundabout**

*Coriolis is most often encountered in earth systems (e.g. weather and navigation) but affects every rotating body.*







# Principles of Micromachined CVG

HSG



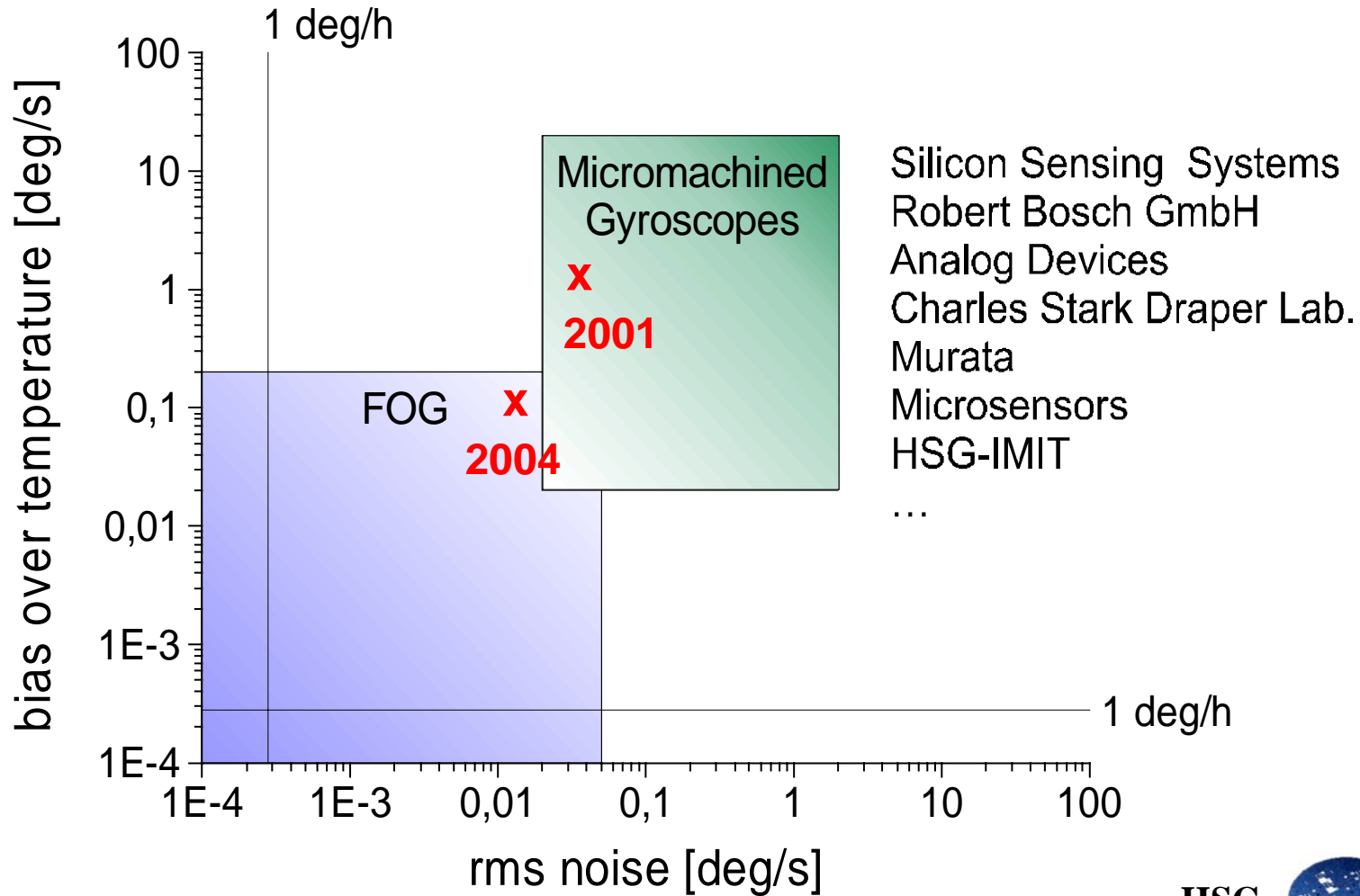
IMIT

**BAE SYSTEMS**

Primary Mode	Rotating	Vib. Shell	Flexural Vibration		Linear Oscillation			Rotary Oscillation	
Features	levitated				1 proof mass	2 proof masses antiparallel		out of plane	in plane
Fig.									
Secondary Mode			Flexural Vibration		Linear Osc.	Linear Osc.	Rotary Osc.	Rotary Osc.	Rotary Osc.
BMM (Bulk Micro Machining)		BASE	T. Seiki	Daimler		Neuchâtel Bosch	Toyota/ Tohoku	CSD VTI JPL/UCLA	
SMM (Surface Micro Machining)	SatCon Sheffield	Michigan			Murata HSG-IMIT Samsung Berkeley ADI		CSD Bosch HSG-IMIT		Motorola Berkeley Bosch HSG-IMIT CSD Samsung

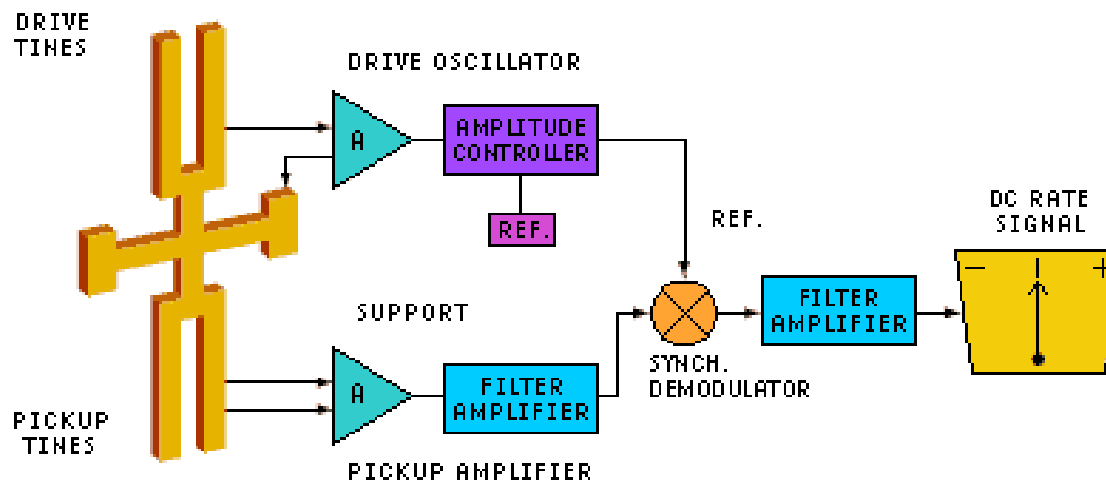


# Performance of Micromachined CVG





# BEI GyroChip (Systron Donner Inertial Division)

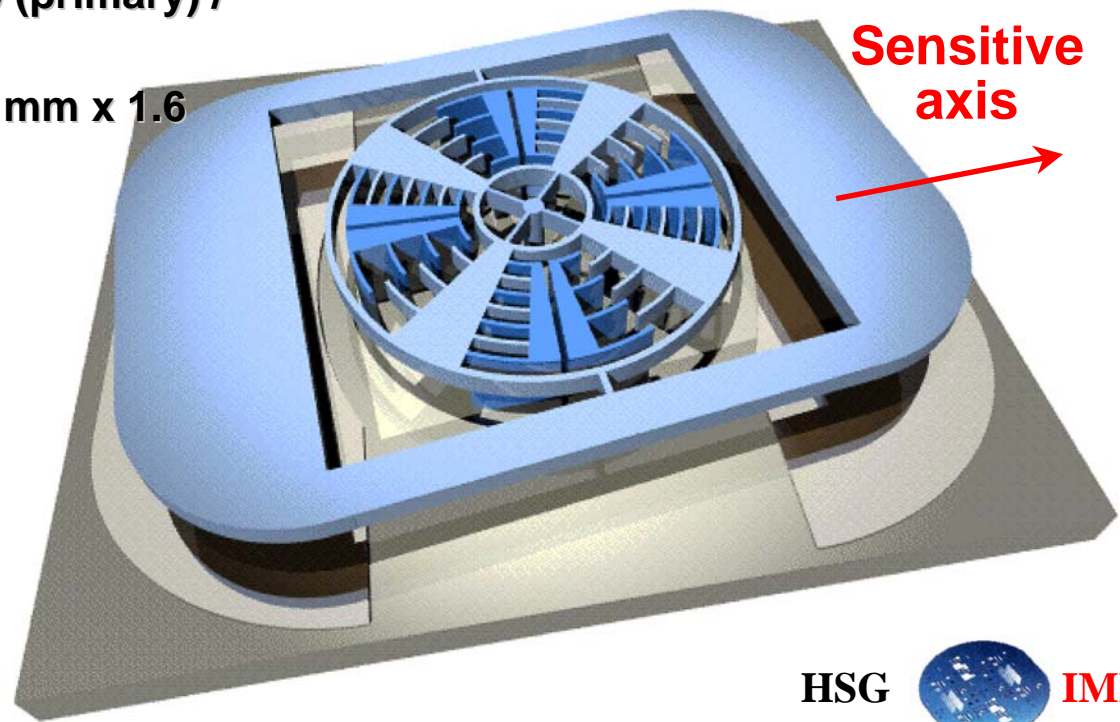


*Vibrating Quartz Tuning Fork (fabricated from thin-film single-crystal PZT quartz)*



# DAVED-RR: Principle of operation

**Resonance frequencies:** 2 - 3 kHz  
**Quality factor (at 4 hPa):** 300 (primary) / 10 (secondary)  
**Overall dimensions:** 1.2 mm x 1.6 mm



Excitation Mode

Detection Mode

HSG

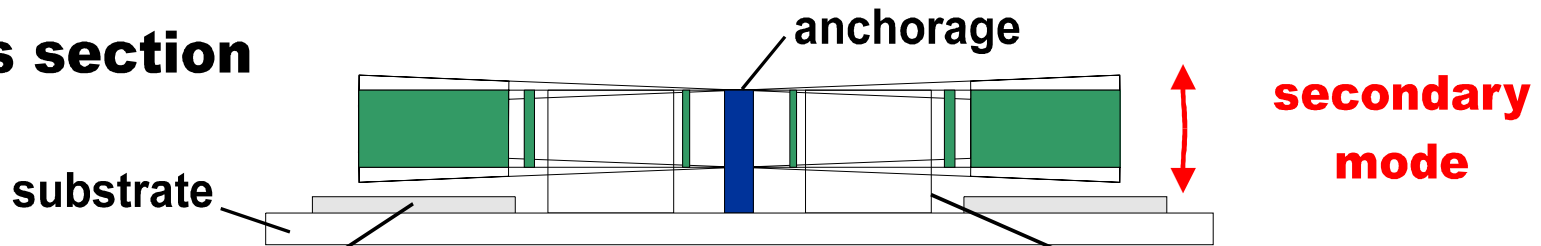


IMIT



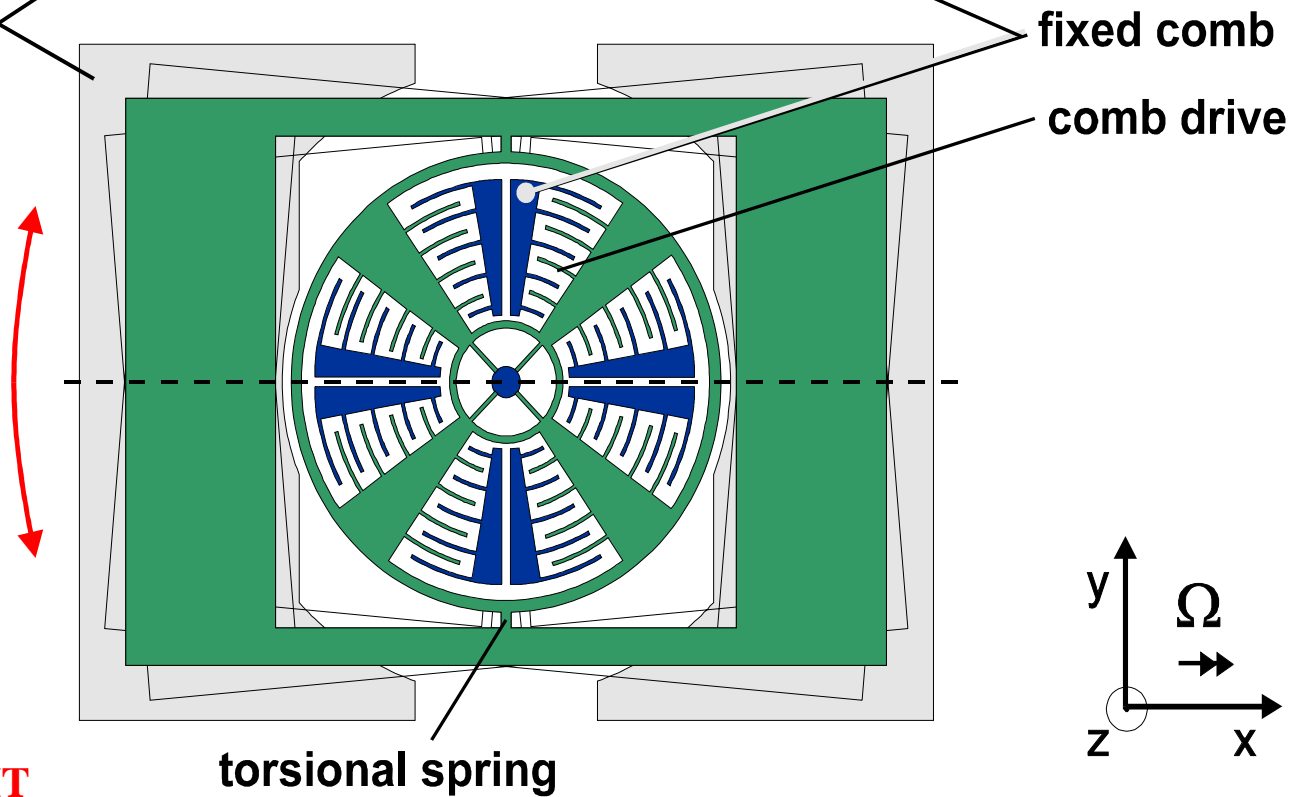
# DAVED-RR – Principle of Operation

**cross section**



**top view**

**primary mode**

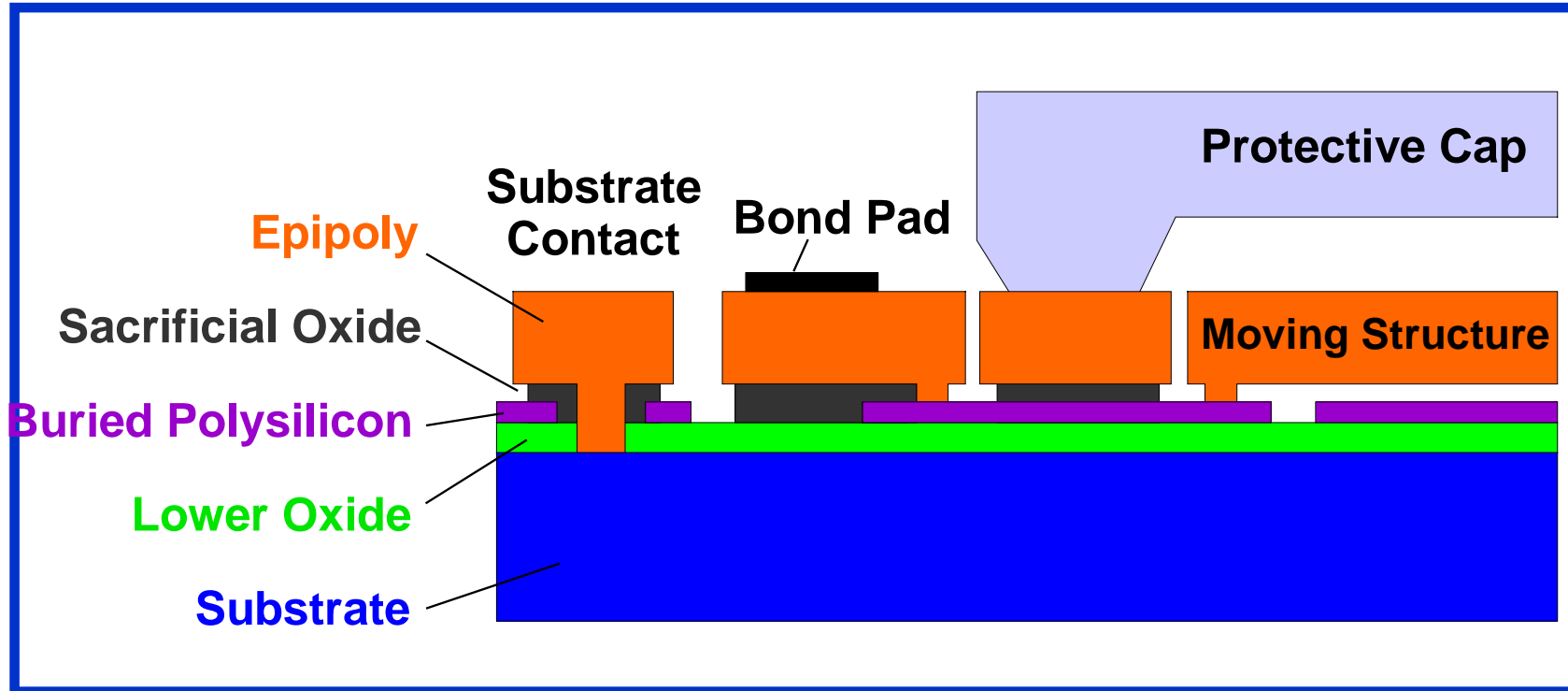




# DAVED-RR: Technology

BAE SYSTEMS

Surface-Micromachining Foundry

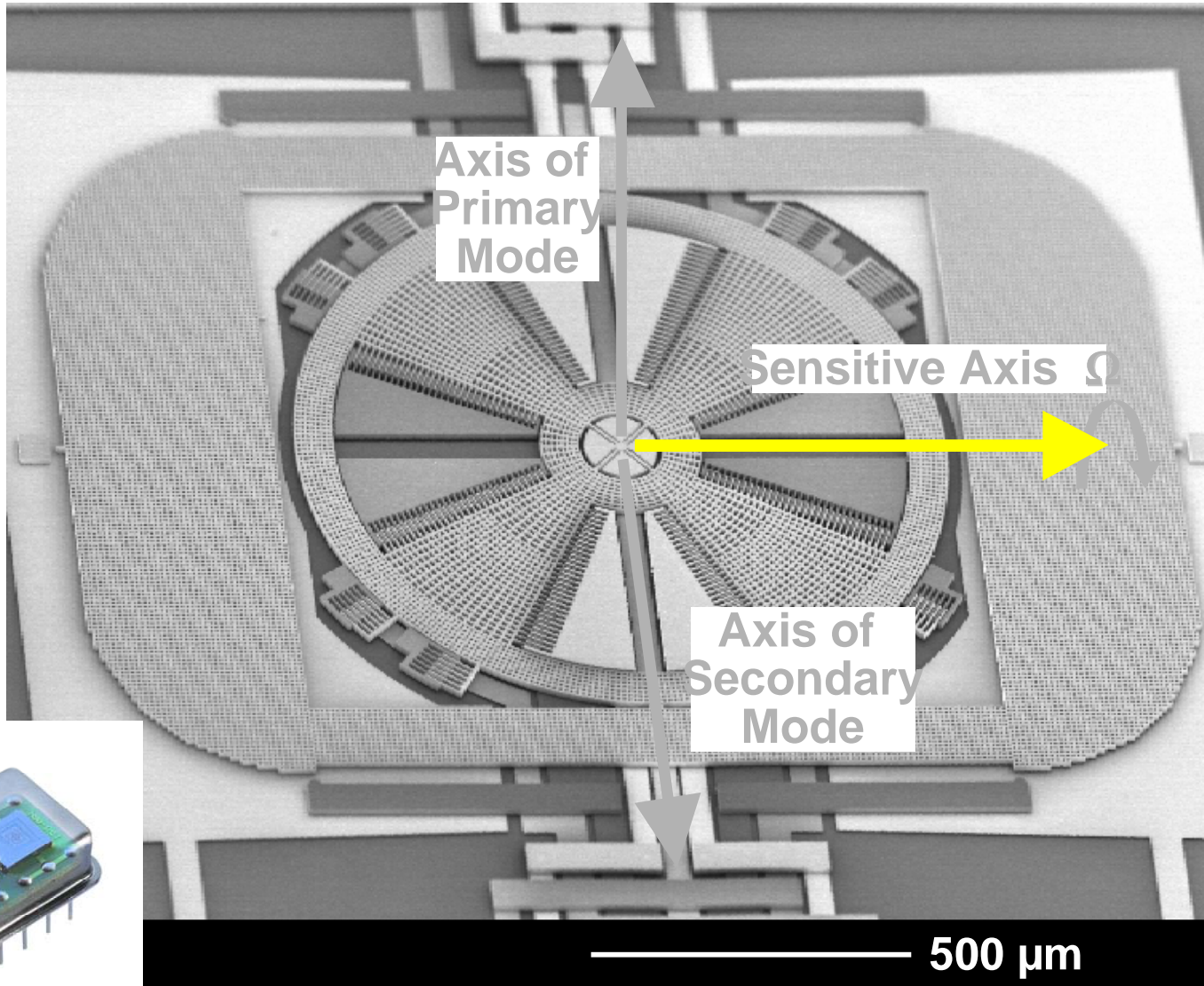


Robert Bosch GmbH



# DAVED-RR: SEM-Graph

BAE SYSTEMS



HSG

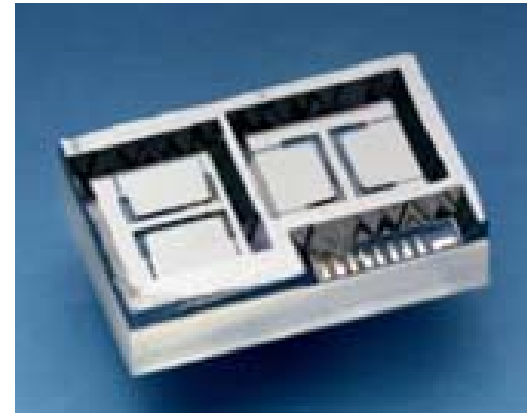
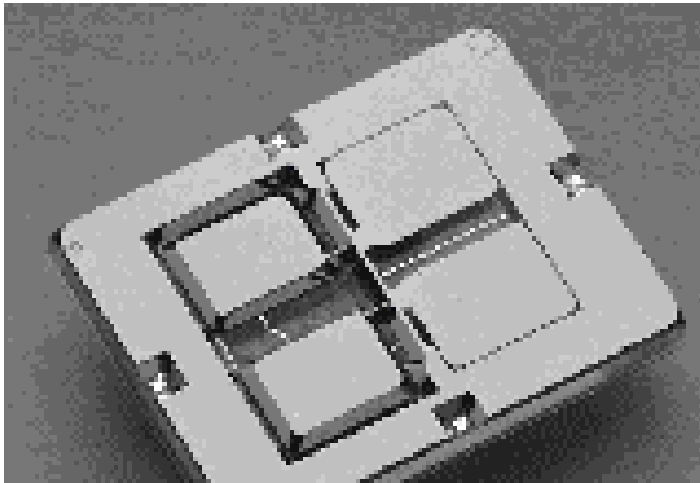


IMIT  
4C-21



**BAE SYSTEMS**

# Imego's 3-axis "Butterfly" Gyro







# Resonant Vs Capacitive

<b>Parameter</b>	<b>Bulk Capacitive</b>	<b>Thin-Film Capacitive</b>	<b>Resonant</b>
<b>S/N Ratio</b>	-	-	+
<b>Accuracy</b>	-	0	+
<b>Self-Test</b>	+	+	+++
<b>ASIC cost</b>	0	+	+
<b>Reliability</b>	0	-	+

# Evolution of VSG Technology



## VSG Evolution

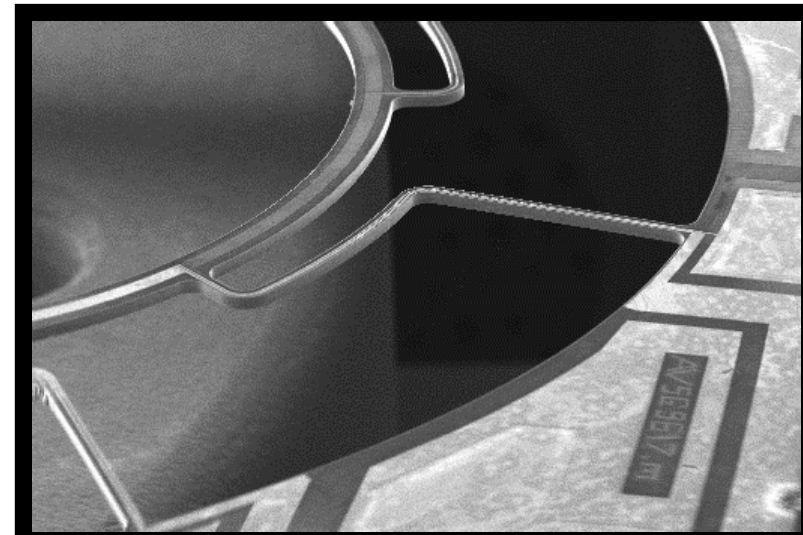
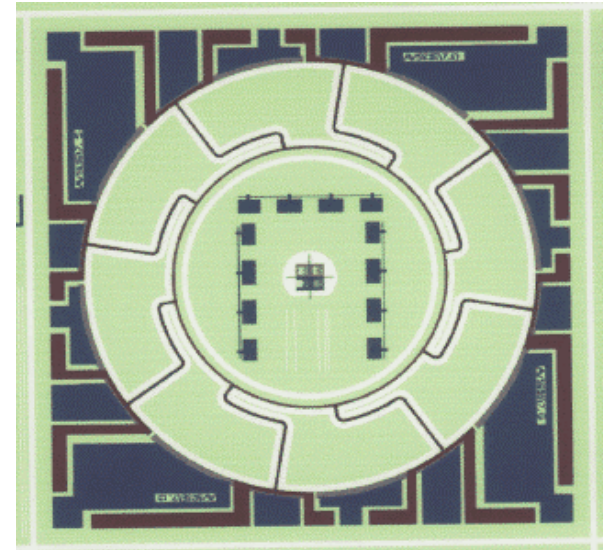
*The SiVSG® shell resonator technology has evolved into silicon from other solid state products; the VSG (piezo-ceramic cylinder) and the RG4550 (metal ring).*



## Si-VSG Gyroscope

BAE SYSTEMS

- Exploits previous experience on solid state sensors
  - shell/cylinder formats
- Adds new process technology
  - Silicon D-RIE Process
- Demonstrated @ 10mm ring (Inductive device)
- Volume production @ 6mm ring (Inductive device)
- R&D @ 4mm ring
  - (Capacitive device)



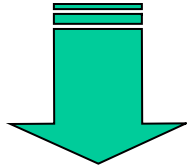


# BAES silicon gyro - a model development

Application knowledge

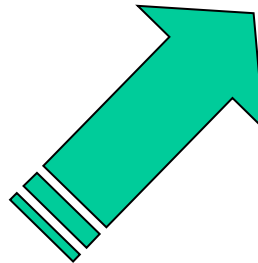


MEMS device expertise



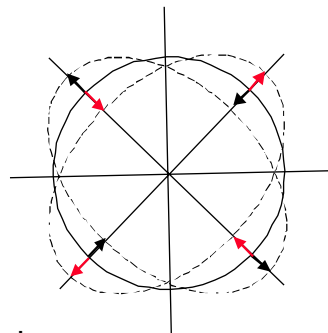
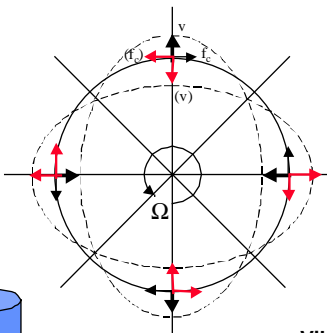
Product understanding

## Vibrating Structure Gyro Principles

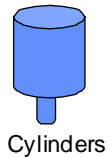
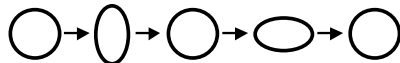


Carrier mode

Response mode



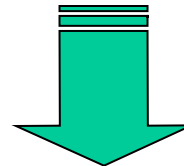
Vibration Cycle



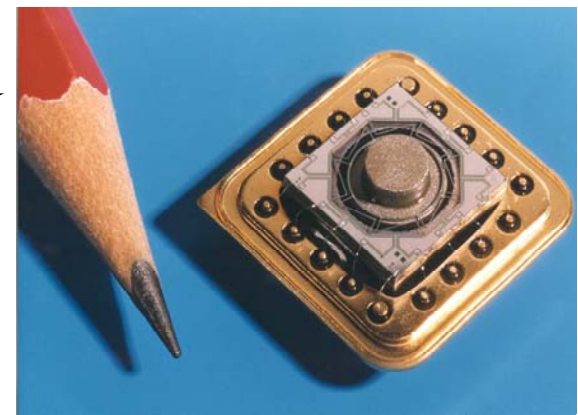
Cylinders



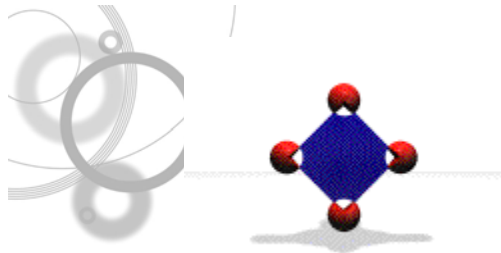
Planar rings



Successful product







# Si-VSG Gyroscope



**Silicon Sensing Systems**  
A Joint Venture between  
**BAE SYSTEMS** and  
**Sumitomo Precision Products**



**Typical Automotive Packaging solution**



**Si-VSG Production Device 6mm Ring**

## **Silicon MEMS Sensors**

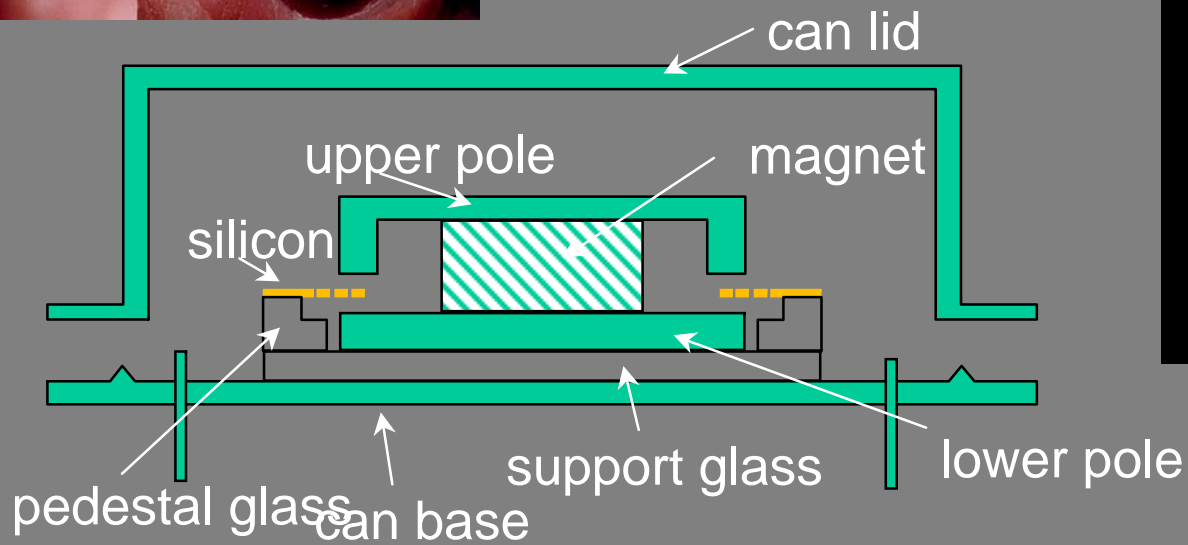
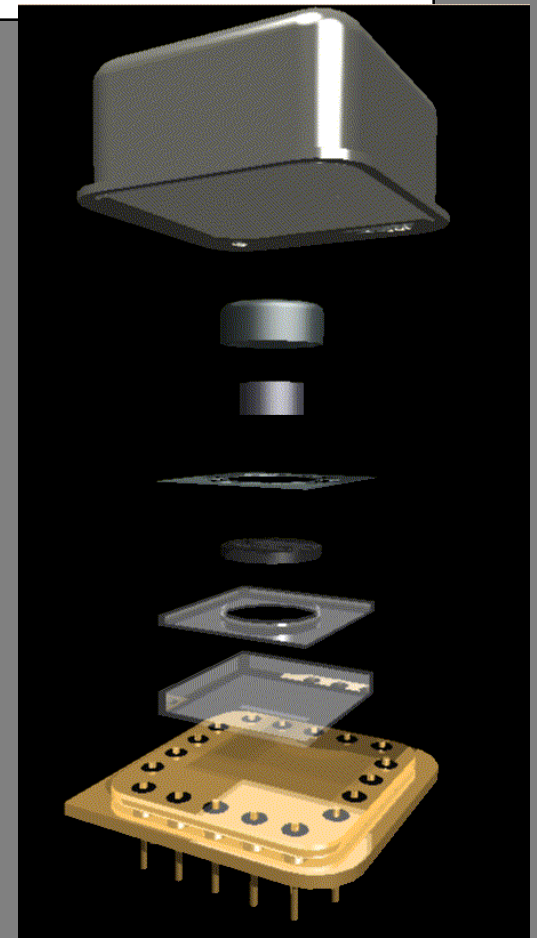
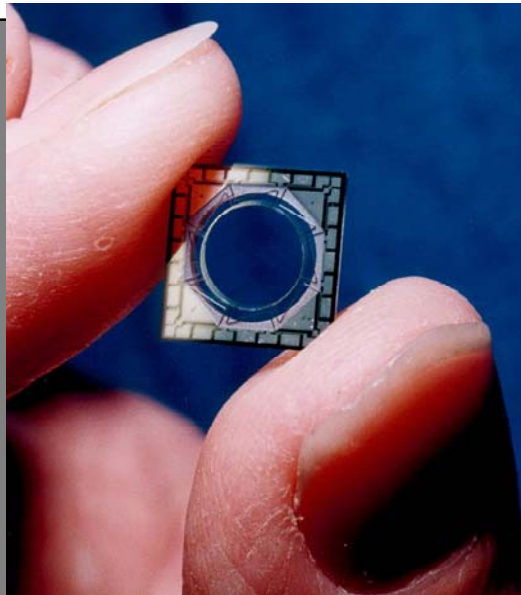
Off-the-shelf, single axis, rate sensors and inertial measurement units.

Excellent shock and vibration performance.

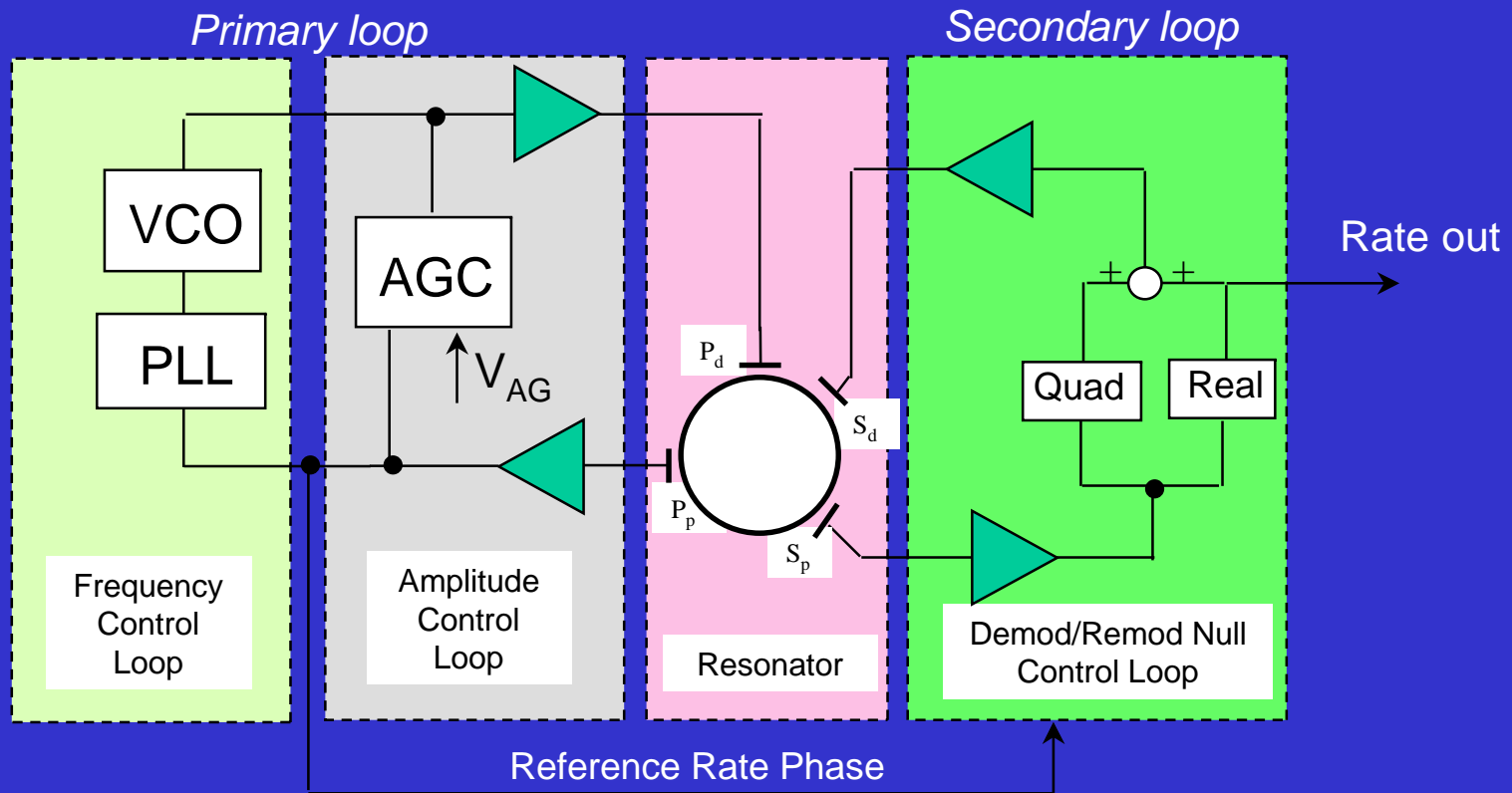
G-hardened to withstand over 22,000g.

Compact, lightweight, with long life and exceptional reliability.

# Silicon Sensor Head



# SiVSG - Systems Schematic



# Achievements and Successes - Military

MR-Trigat (TRIGAN):	Guided firing
VL Seawolf:	Production contract
ERGM:	High-g Launch Controlled Flight (CTV1)
AGS:	Selected for ATD phase
RAM:	HWIL Testing at China Lake Proving Grounds
LCPK:	Successful ITV1 firing
C-KEM:	Static trials at Redstone Arsenal
Netfires:	Under contract for ATD

Either selected or being evaluated for other programs including: Longbow, Javelin, NLAW, WCMD, Small Diameter Bomb, Project X.

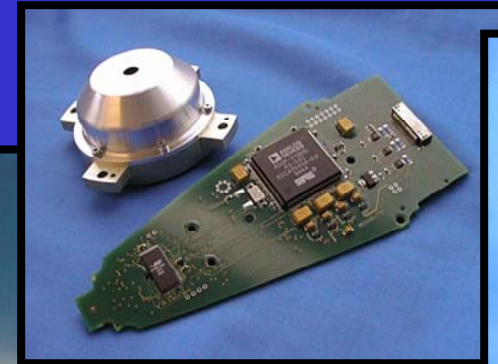




## Controlled High-g Test Firing (White Sands)



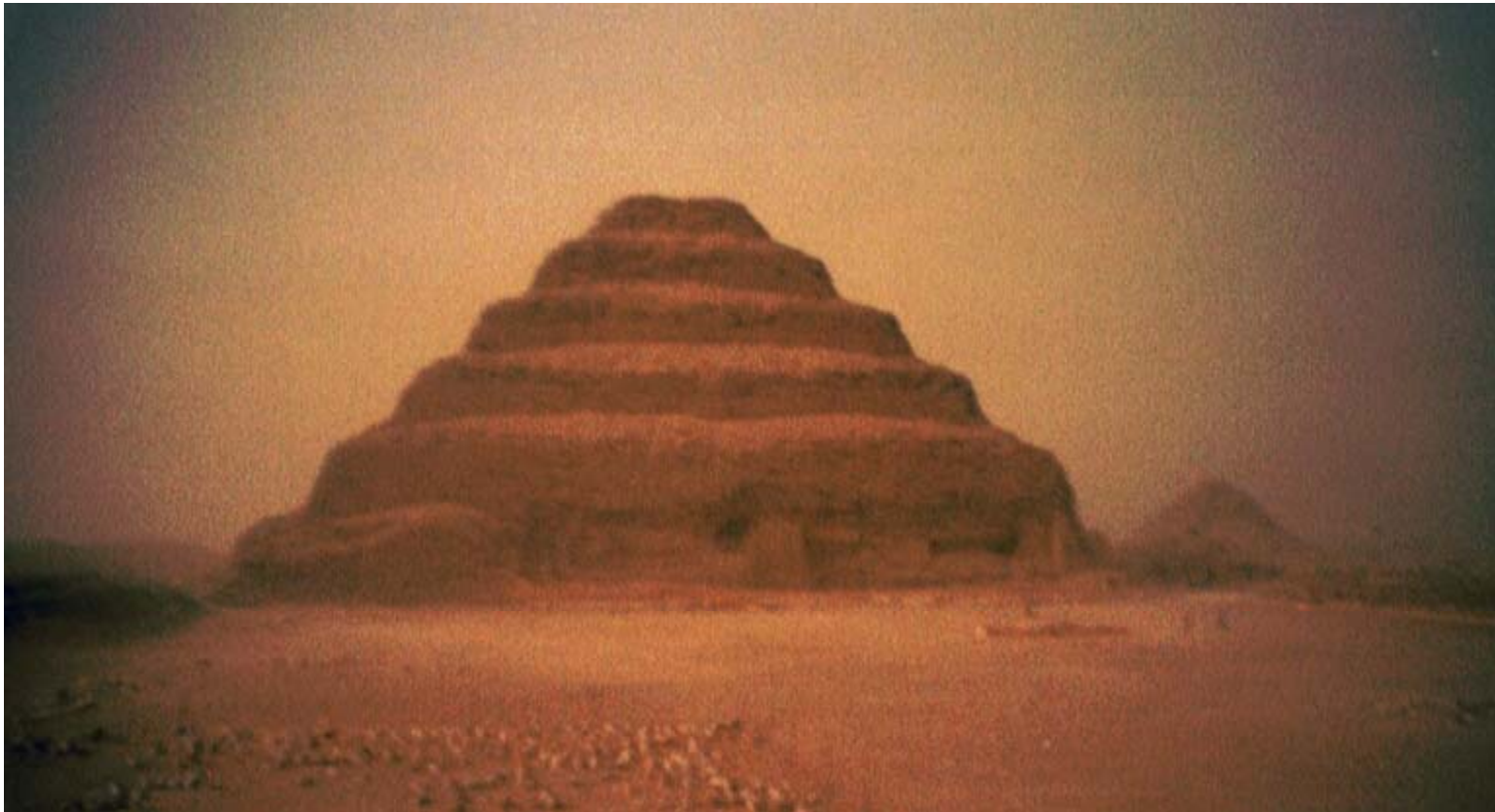
**3-axis HWIL testing at China Lake and Bourges**



- Repackaged SiIMU01
- Selected as baseline for Raytheon's ERGM program
- G-hard package



**Guided Missile Firing**





# MEMS Aerospace Applications

## *Les Applications Aérospatiales des MEMS*

An AVT-105 Lecture Series No. 235

organised by the

Applied Vehicle Technology Panel

*Part 4 (and final)*

*IMUs*



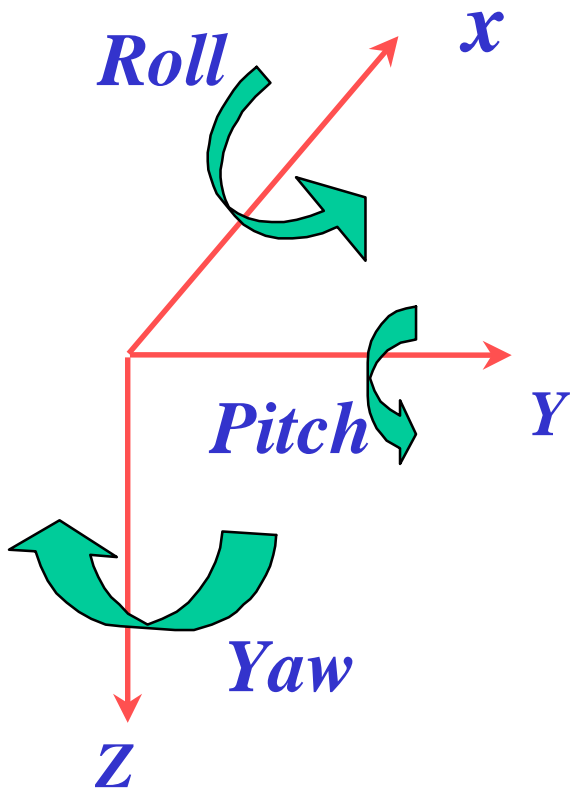


## **Strap-Down Systems**

- **Inertial Measurement Units measure motion in three orthogonal axes**
- **Relies on three single-axis gyros mounted “strapped down” orthogonally (X, Y and Z)**
- **Together with 3 (orthogonal) accelerometers, the six sensors form a sensor co-ordinate system.**
- **Attitude-Heading Reference Systems (AHRS) measures the dynamics of a system by augmenting heading using a magnetic compass or GPS**
- **Inertial Navigation Systems integrate GPS data to calculate orientation and position**



## **INERTIAL MEASUREMENT UNITS**



**SIX INERTIAL SENSORS :**

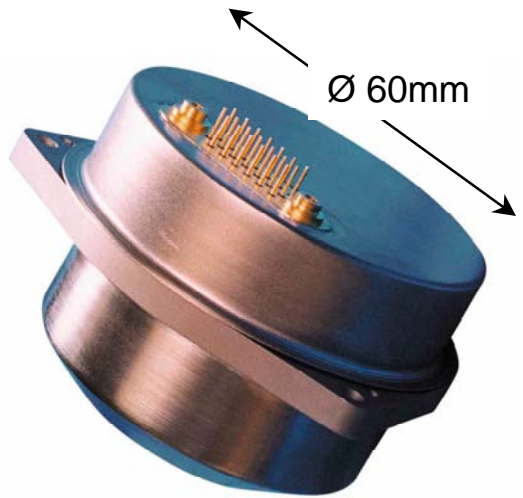
*3 linear accelerometers*

+

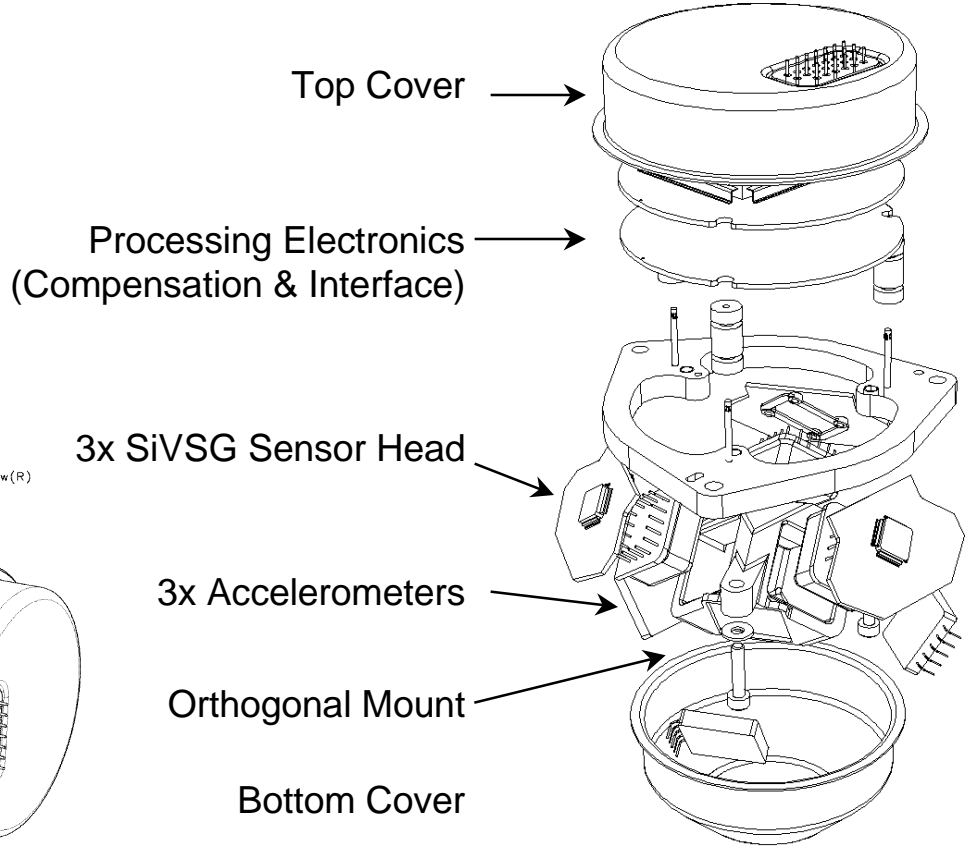
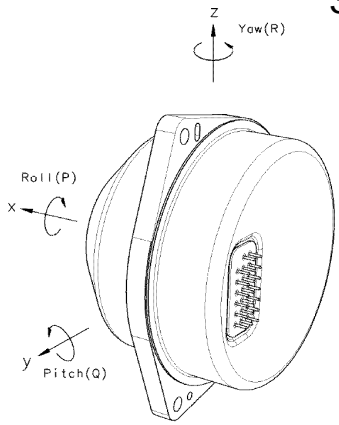
*3 rate gyros to measure rotational velocity*

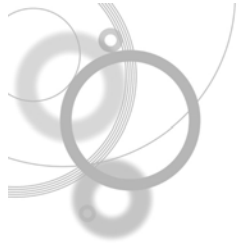


# SiIMU01 - All-MEMS Inertial Measurement Unit



100°/hr  
10mg  
<250grams





# Honeywell's IMUs

*The HG1900 is a MEMS gyro based Inertial Measurement Unit suitable for various commercial and military guidance and navigation applications. It uses **Honeywell** MEMS gyros and RBA500 accelerometers.*



*The HG1910 is a Gun Hard MEMS Inertial Measurement Unit used for which is suitable for guided projectile applications*







# Crossbow's AHRS

*The **Crossbow** Solid State Gyro, known as an Attitude-Heading Reference System, or AHRS, uses 3-axis accelerometer and a 3-axis rate sensor to make a complete measurement of the dynamics of a system. The addition of a 3-axis magnetometer inside the Crossbow AHRS allows it to make a true measurement of magnetic heading without an external flux valve. The Crossbow AHRS is a solid-state equivalent of a vertical gyro/artificial horizon display combined with a directional gyro and flux valve.*

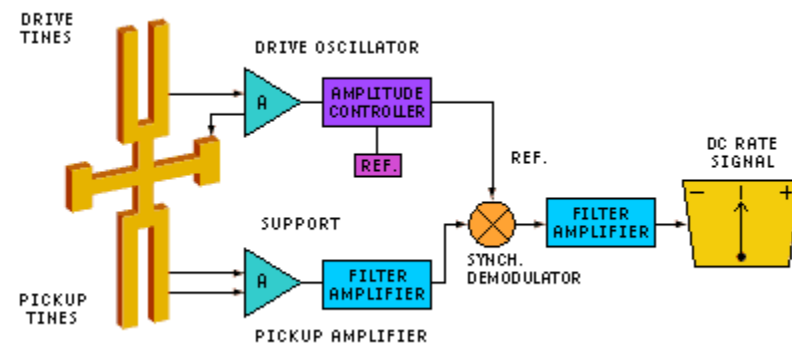


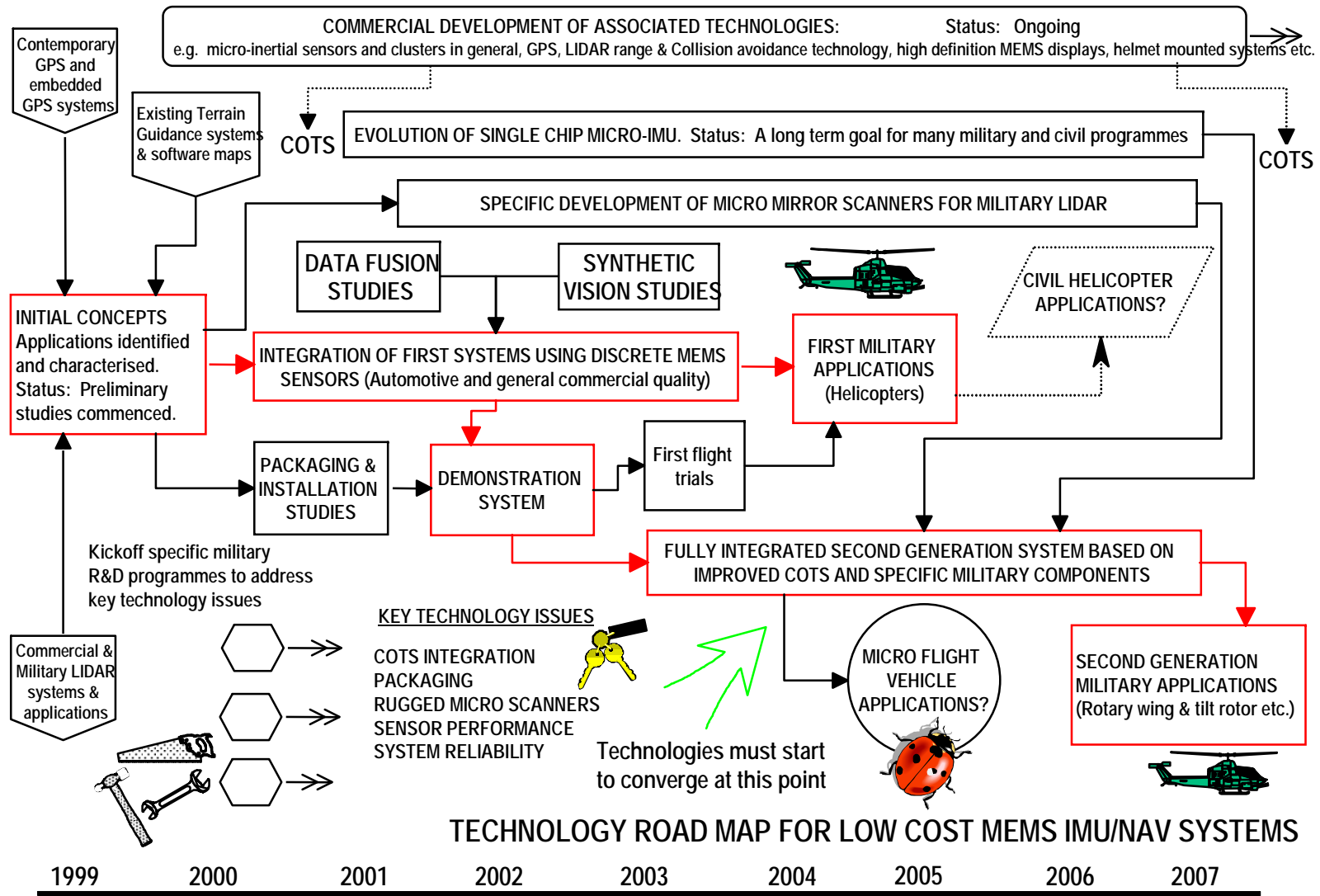


# BEI Systron Donner's Digital Quartz IMUs



- *Tactical missiles*
- *Precision guided munitions*
- *Unmanned vehicles*
- *Land vehicles*
- *Avionic systems*
- *Range instrumentation systems*

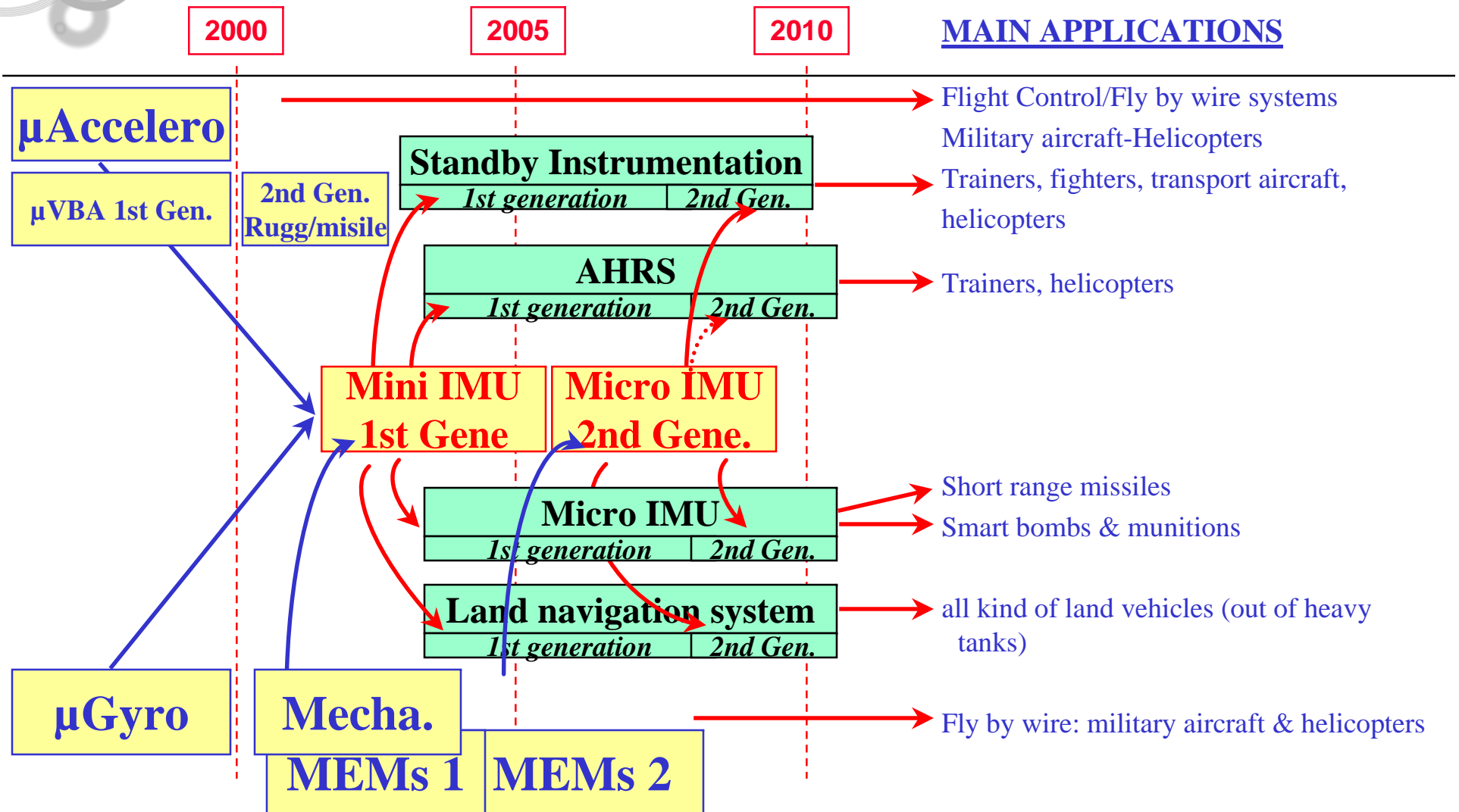




**TECHNOLOGY ROAD MAP FOR LOW COST MEMS IMU/NAV SYSTEMS**

# IMUs development/applications

BAE SYSTEMS





Sculpting a match-stick

***Thank You***

***Ayman El-Fatatry***